



The Abdus Salam
International Centre for Theoretical Physics



SMR/1758-17

**"Workshop on Ion Beam Studies of Nanomaterials:
Synthesis, Modification and Characterization"**

26 June - 1 July 2006

**Nanoclusters and -tubes for
Swift Heavy Ion Track Electronics
(SITE)**

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Berlin, Germany***

Nanoclusters and -tubes
for
Swift-Heavy Ion Track Electronics
(SITE)

D.Fink, HMI Berlin

Contents

■ Basic SITE concept

Latent and etched tracks / etched track filling / applications

■ Nanoclusters

Quantum electronic devices / Sterilizing foils / NCs for tailored conductivity / NC architecture

■ TEAMS & TEMPOS

Current-Voltage characteristics / theory / sensors

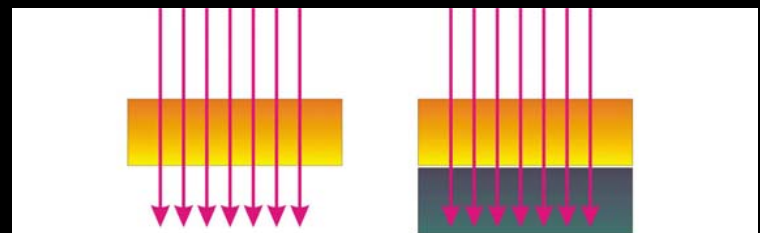
■ Negative differential resistances

electronic devices / Sterilizing foils / NCs for tailored conductivity / NC architecture

■ Nanotubes

CNTs in TEMPOS structures / PCVD and thermal CVD / field emission / 3D nanoelectronics

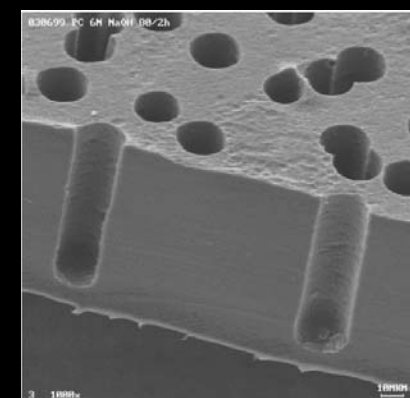
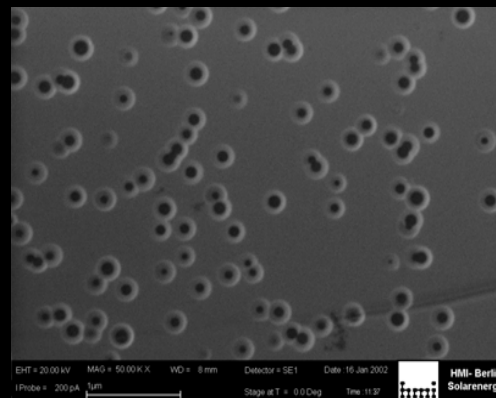
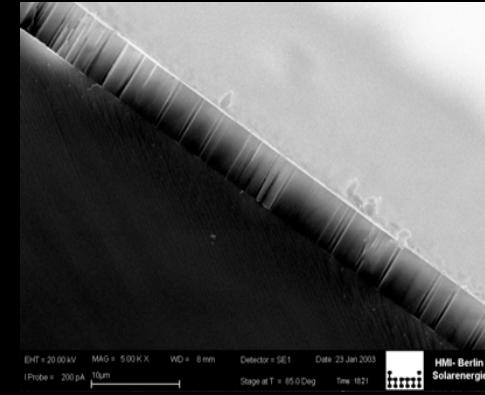
The basic concept of SITE:



irradiate insulator with swift heavy ions
(carrier-free or on semiconductor substrate)



Etch the latent tracks, fill them with
(semi)conductors, contact both sides



Why Swift Ion Track Electronics (SITE) ?

There are at least 4 competing techniques in nanoelectronics:

- a) self organizing nanostructures
- b) nanomanipulations
- c) nanolithography
- d) molecular electronics

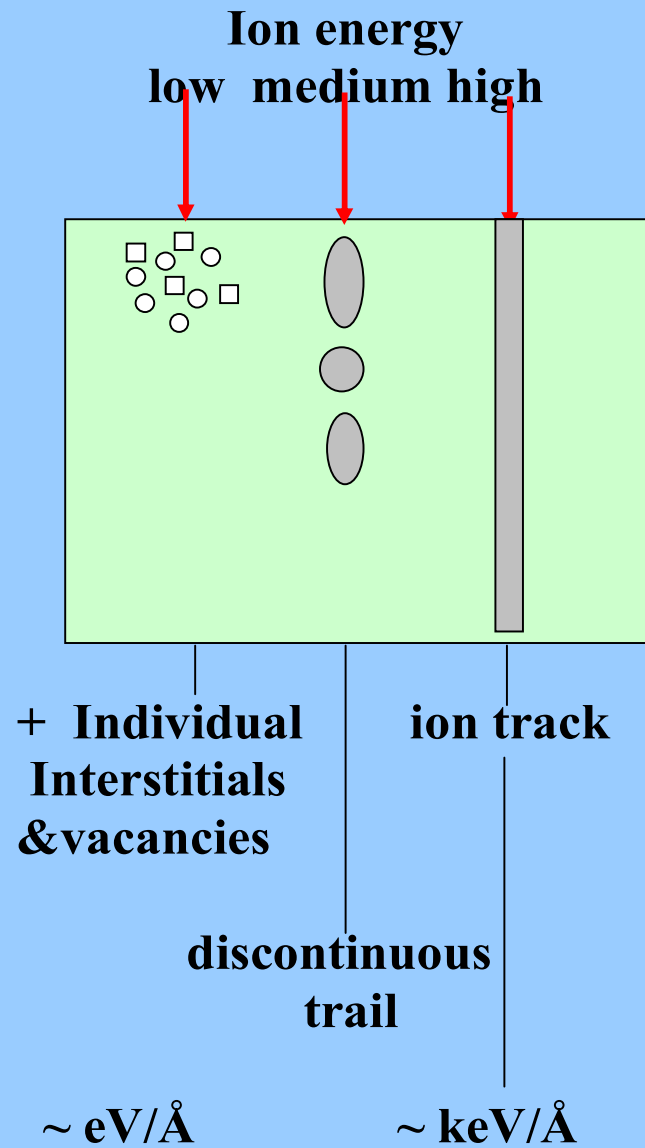
all these 4 techniques are excellent, but –

a,d) restricted to relatively few systems

b.c,d) very difficult, time consuming and expensive

For contrast, SITE has a number of advantages which make this technique interesting:

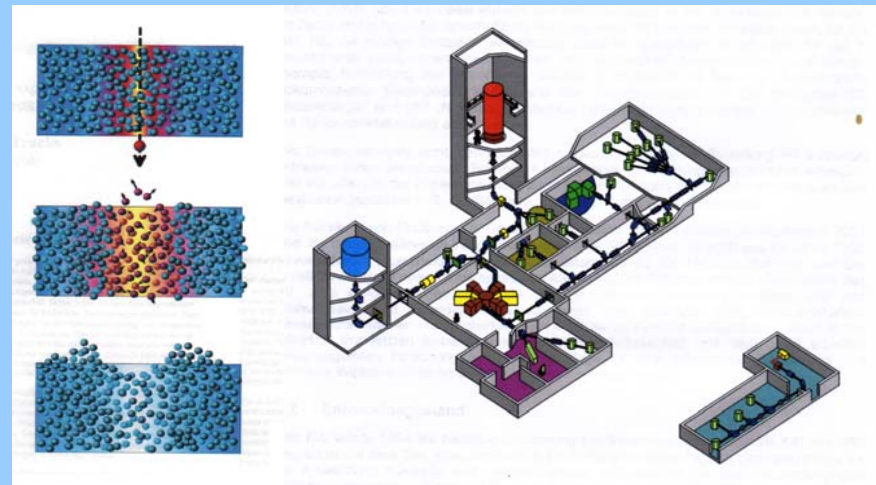
- *Simple* *fast* *cheap ($10^{-9...10}$ €/track (for $10^{6...7}$ cm⁻²))*
- *precise* *light-weight* *large area devices (> 1 m x 100 m)*
- *mechanically flexible* *environmentally friendly*
- *... and has an extremely high variability in its parameters*



Swift Heavy Ions:

continuous damage
high energy transfer
high aspect ratio
 $r \approx \text{nm}$ $l \approx 100 \mu\text{m}$
permanent damage
(also recombination)

↓
"latent tracks"



SITE: Great variability in material's properties

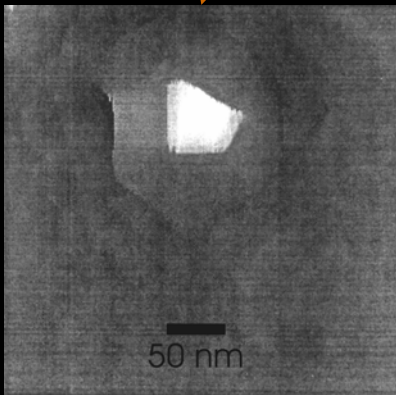
- Host material for tracks..insulators, semiconductors
- polym., SiO₂, SiON, organomet., C₆₀, SnO₂,...
- Substrate..... Self-supporting, Si, glass, metal
- Track type.....latent $\leftrightarrow$ etched tracks
- Track shape.....conical, cylindrical, funnel-like,..
- Inner track material.....metals, semicond., electrolytes
- Ag, Au, Pd, Ni, C₆₀, CNTs, Phthcy, SnO₂, TiO₂, CdS, organometals, cond. Polymers, nanocomposites,.....
- Inner track structure.....wires, fibrilles, nanotubules, nanoclusters, gel, liquid; axially or radially structured
- Track density.....individual or overlapping tracks
- Applications.....Passive, active electronic elements
- resistors, capacitors, inductors, sensors, transformers, diodes, transistors
- Peculiarity:.....hybrides with Si electronics possible
- Novel track-specific applications: TEAMS & TEMPOS

Latent Tracks

**Radiochemical
changes**

*Dangling
bonds →
sensors*

*Chem. React.
Polysil. → SiC*



**Structural
changes**

*Rad.induced free
volume →
incorporate matter*

**Phase
Transitions**

*Defects →
trap matter*

*Diam., C₆₀ →
conducting phases*

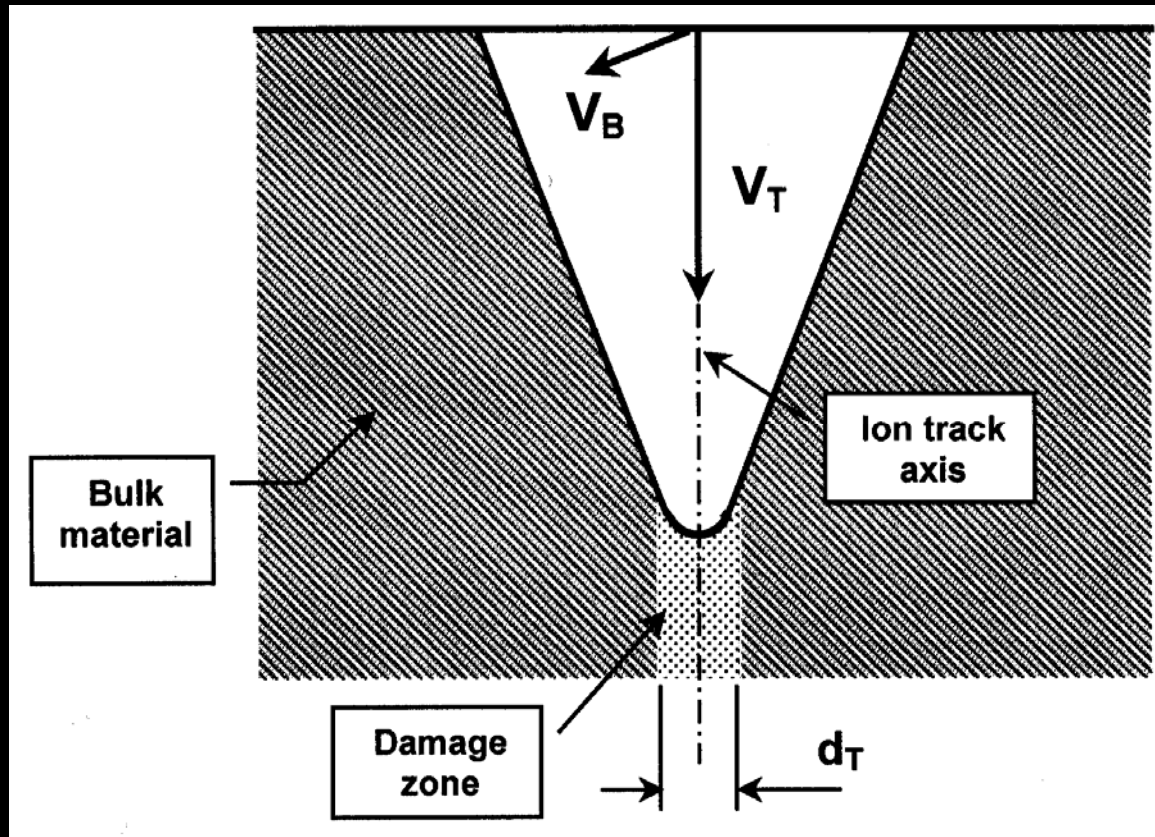
*If matter is (semi)conducting →
(semi)conducting nanowires*

Medium becomes electronically anisotrop

Production of etched tracks

Strong etching enhancement around track

→ pore formation



A scanning electron micrograph (SEM) showing numerous dark, circular etched ion tracks of varying sizes distributed across a lighter, textured background. The tracks appear as well-defined, dark circles, some with slightly irregular edges, suggesting they were formed by the etching of latent tracks left by ionizing radiation.

Etched ion tracks in PET

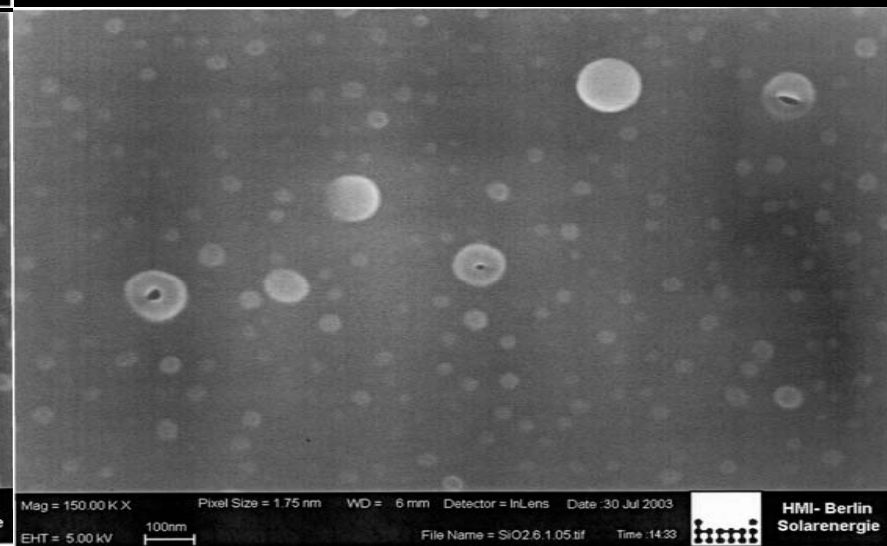
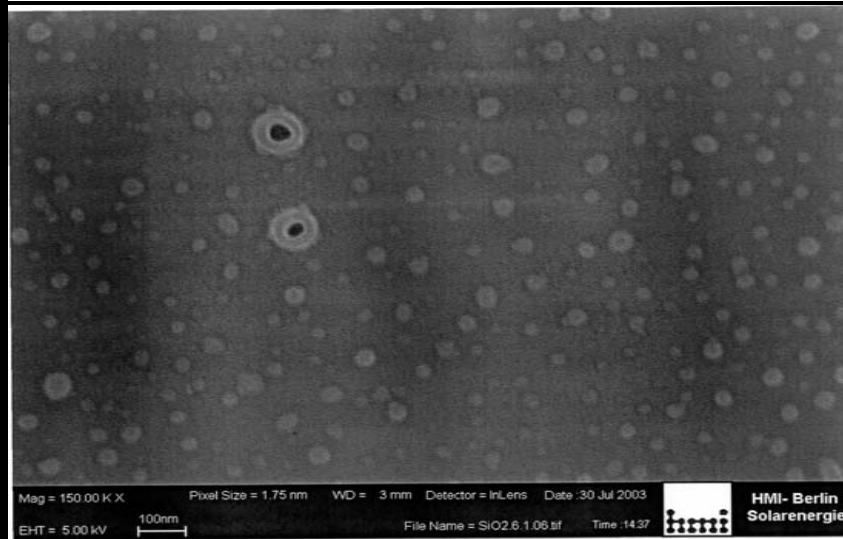
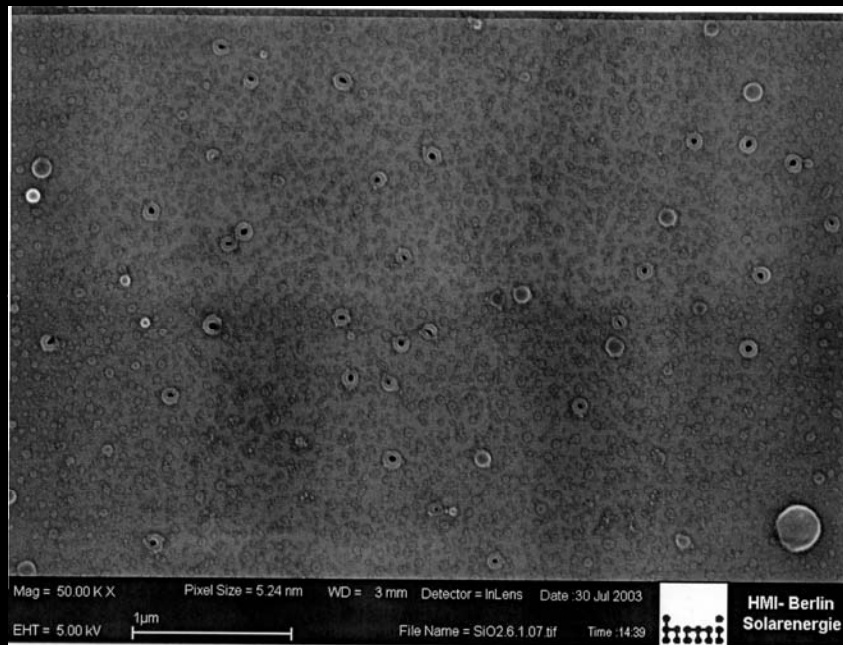
EHT = 20.00 kV MAG = 4.72 K X WD = 8 mm Detector = SE1 Date : 16 Jan 2002
Probe = 200 pA 10µm Stage at T = 0.0 Deg Time : 11:58

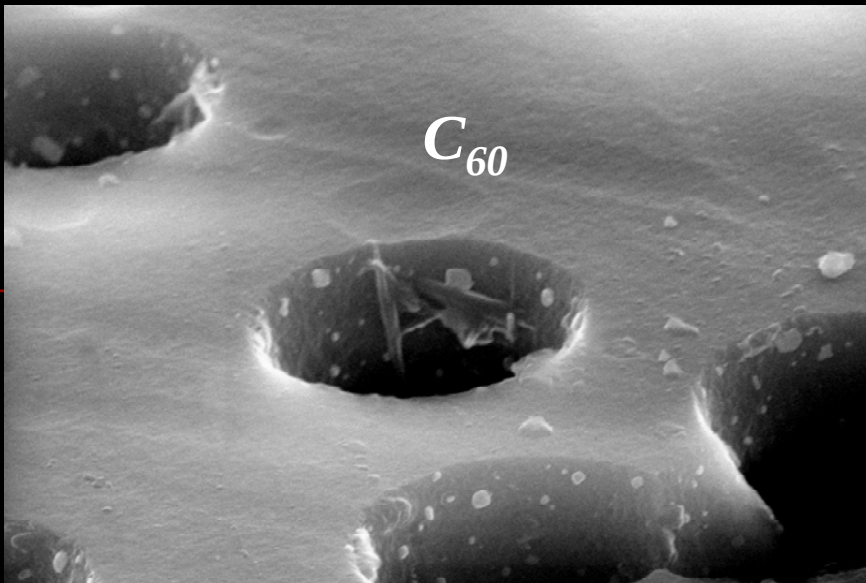


**HMI- Berlin
Solarenergie**

Etching of ion-irradiated SiO_2 surface.

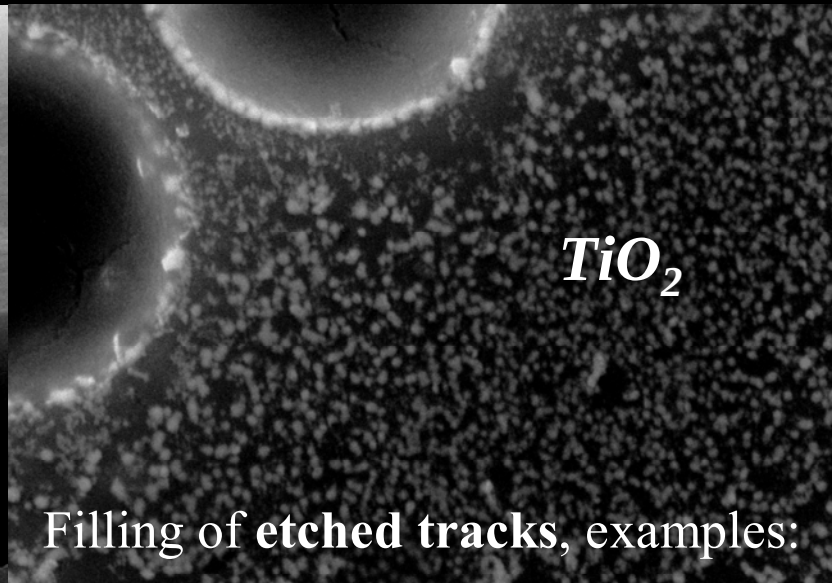
Intrinsic defects yield
etch pits, ion tracks
yield conical pores.





C_{60}

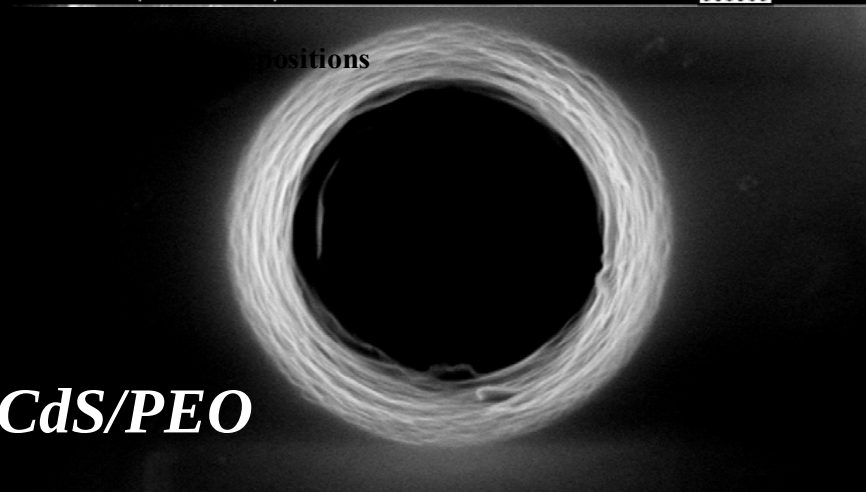
EHT = 20.00 kV MAG = 20.01 K X WD = 9 mm Detector = SE1 Date: 16 Jan 2002
 IProbe = 200 pA 2µm Stage at T = 60.0 Deg Time: 10:00 HMI- Berlin Solarenergie



TiO_2

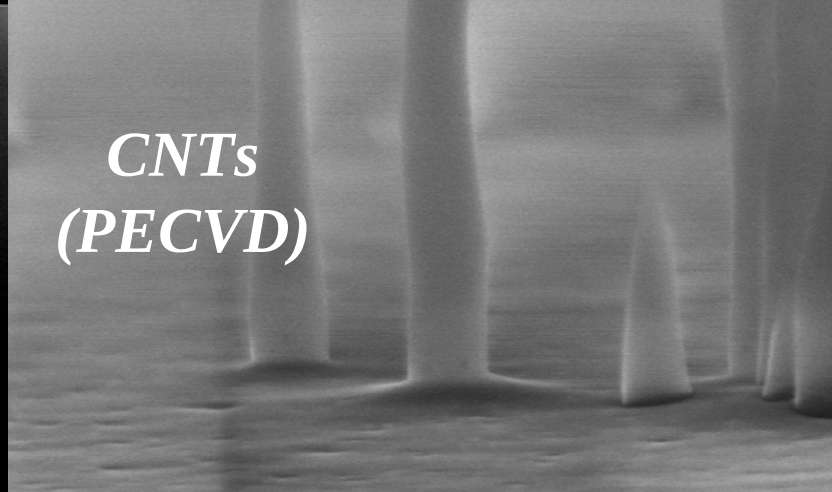
Filling of etched tracks, examples:

EHT = 20.00 kV MAG = 20.12 K X WD = 9 mm Detector = SE1 Date: 26 Oct 2001 HMI- Berlin



CdS/PEO

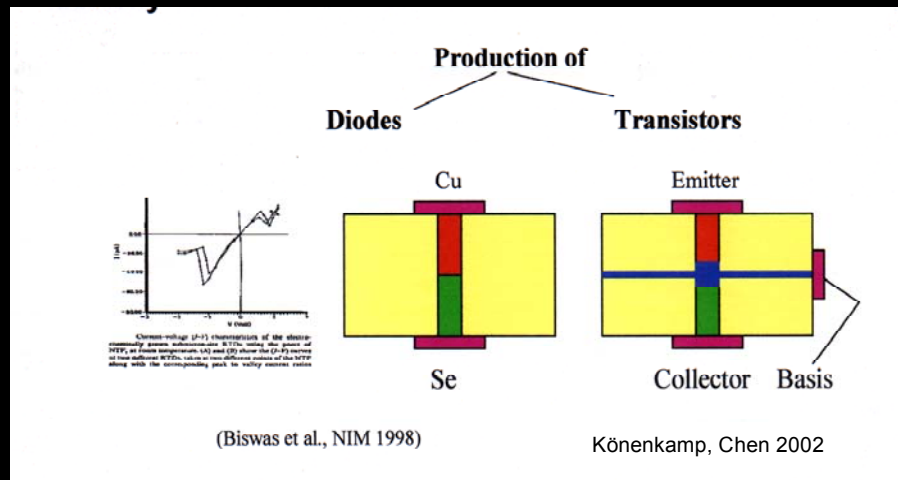
EHT = 25.00 kV MAG = 40.00 K X WD = 11 mm Detector = SE1 Date: 3 Jun 2003
 IProbe = 50 pA 2µm Stage at T = -0.0 Deg Time: 10:50 HMI- Berlin Solarenergie



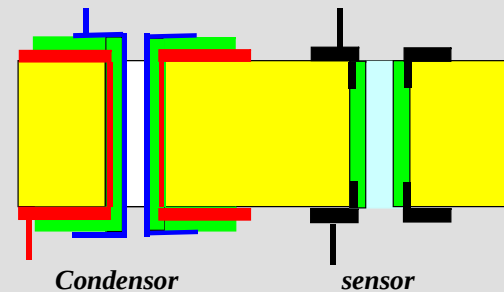
$CNTs$
 (PECVD)

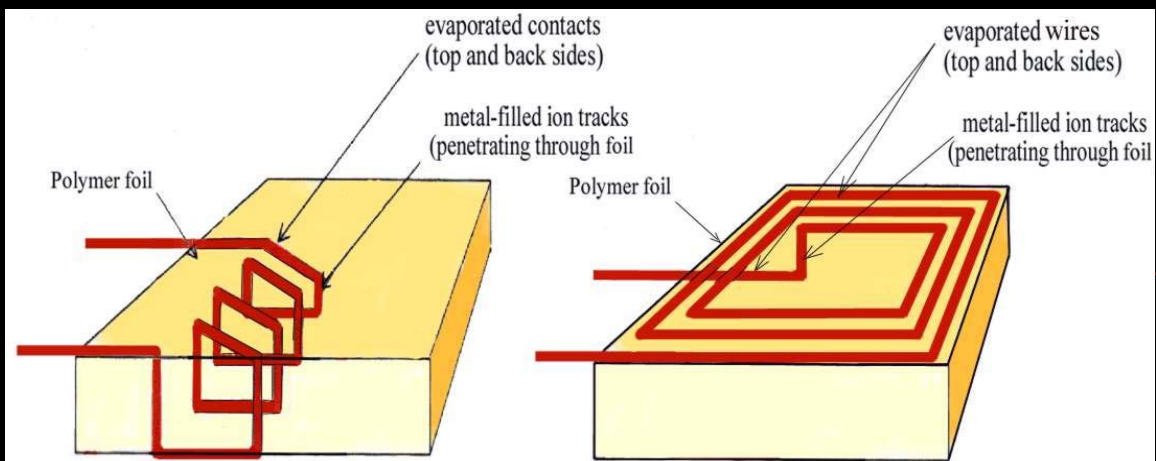
SKKU SEI 15.0kV X100,000 100nm WD 7.6mm

On the way to devices: axially and radially modified structures

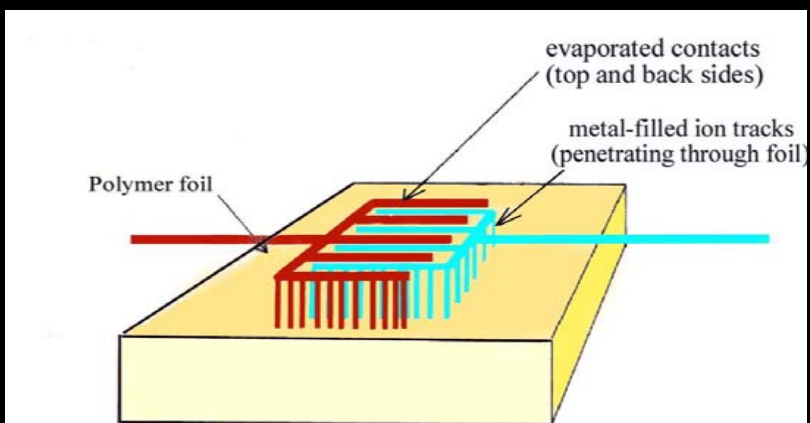
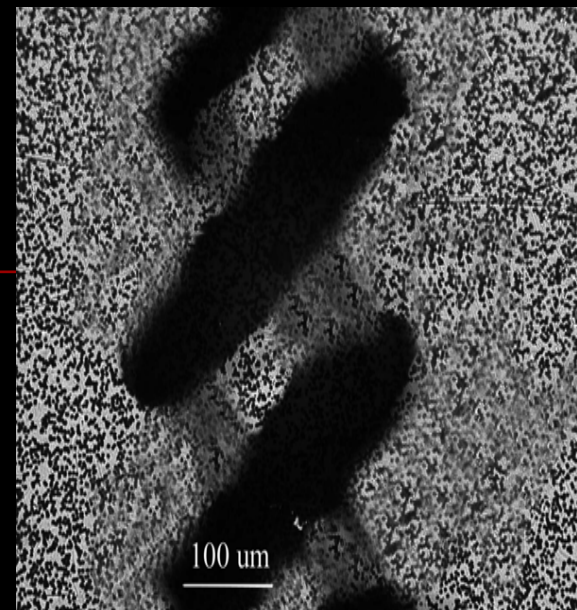


On the way to devices: radial structuring

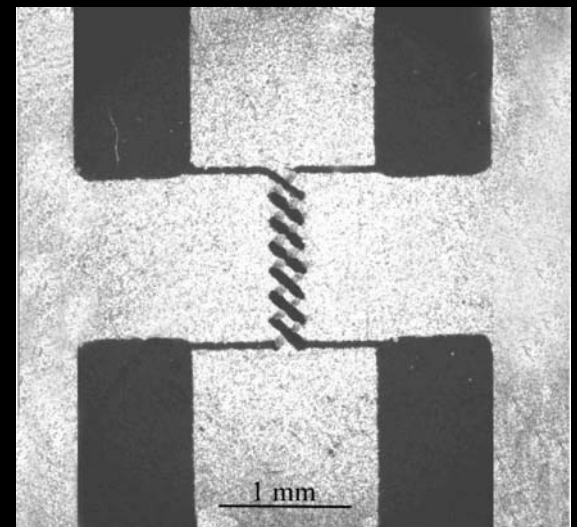




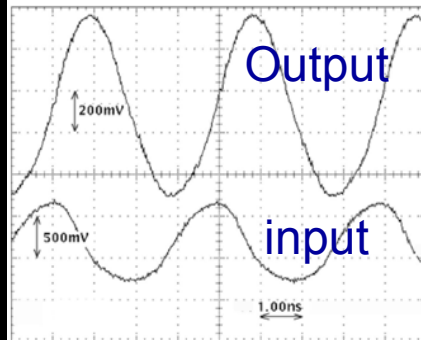
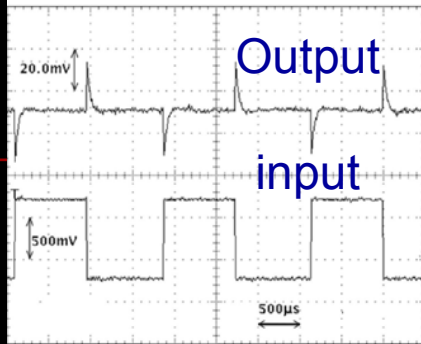
ion track magnets



ion track condensor

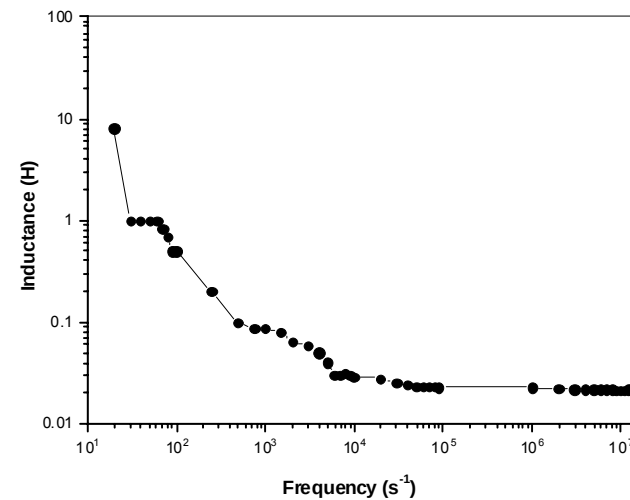


Response of Ion track-based microtransformer



Frequency dependence
of the coil
inductivity

Comparison of input and output signals
for rectangular
and sinusoidal input at various frequencies



Why nanoclusters for SITE?

Microscopic:

- Quantum effects can be exploited

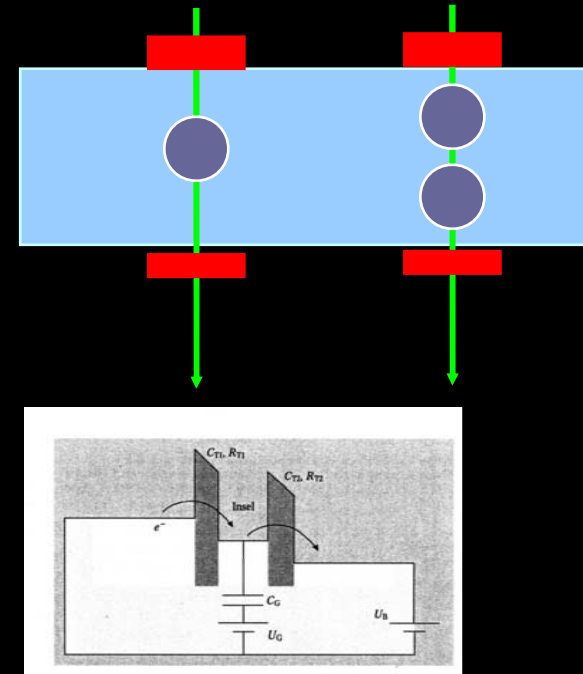
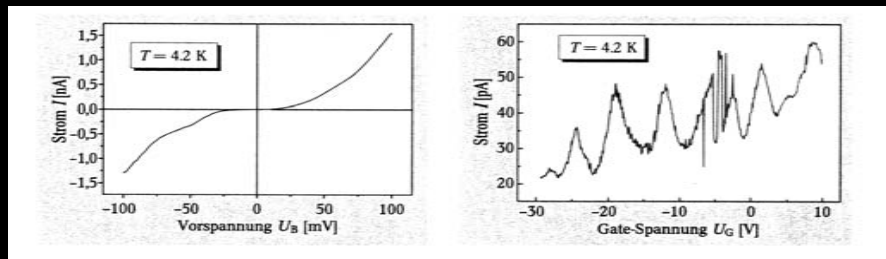
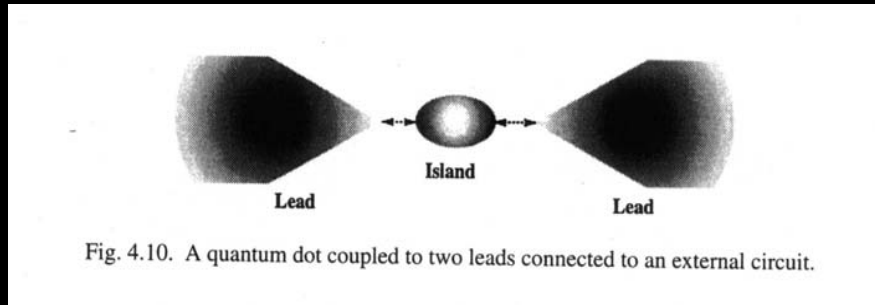
Macroscopic:

- Higher overall surface of NCs
- Conductivity can be tailored:
well-defined order of magnitude, voltage and temperature dependence
- NCs store a considerable amount of charge
- NCs can be used as „building bricks“ for construction of refined structures
conducting nanowires,...

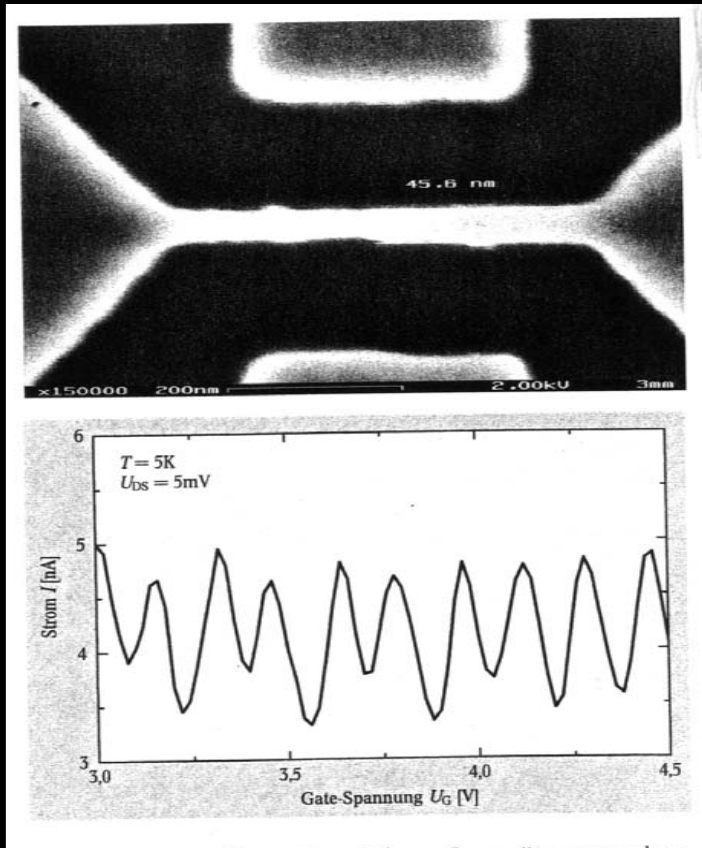
Quantum confinement: single electron transistor

From:

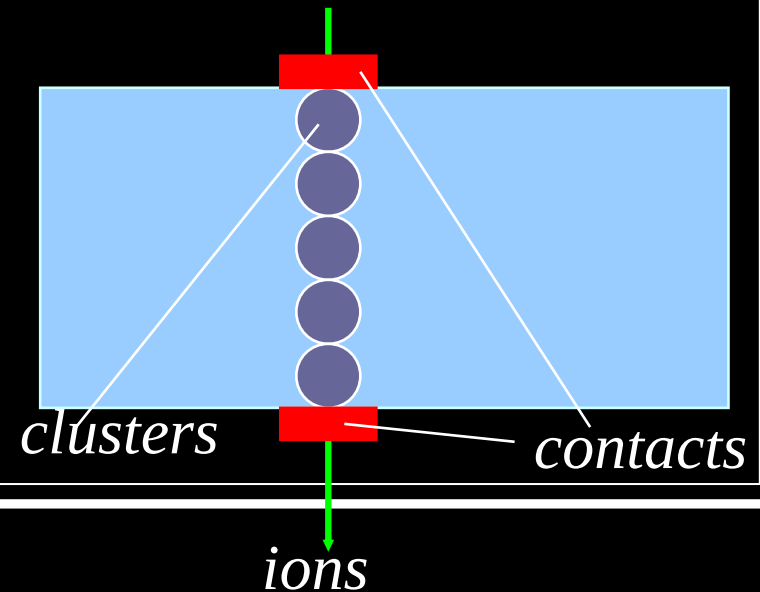
D.K.Ferry, M.Goodnick,
Transport in nanostructures, 1977



Quantum confinement of narrow wires



*Formation of quantum wires
by string of closely touching
nanoclusters ?*

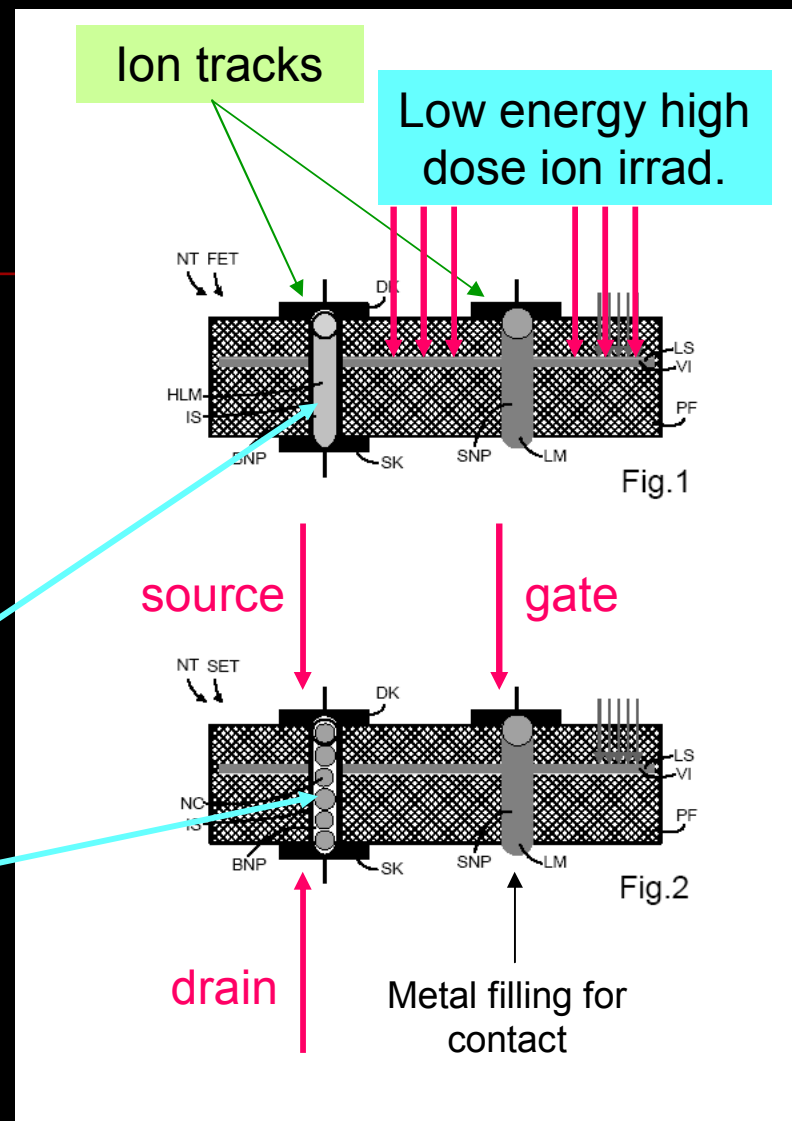


possible realization with ion irradiation:

FET or SET formation by combined –

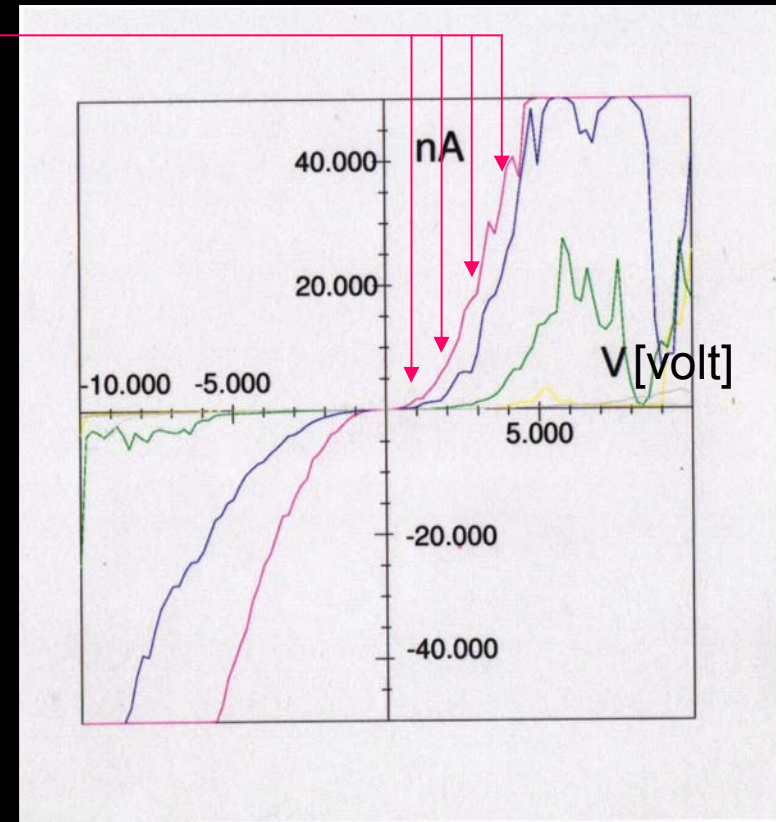
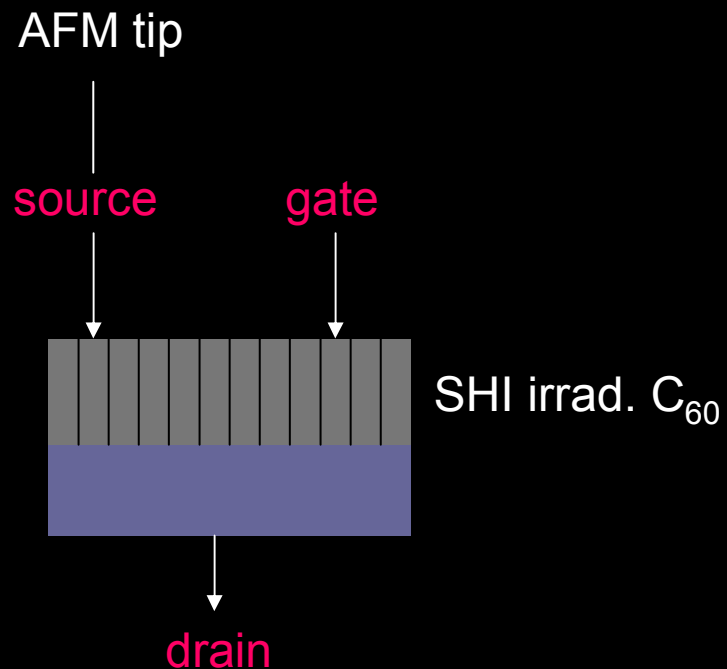
- High energy irradiation
- Etching
- Deposition
- Low energy irradiation
- contacting
- FETs: homogeneous filling
- SETs: nanocluster filling

Patent DE10361934.8-33 (2002)



Quantum electronic ion track device, first result:

Small periodic stairs



Higher overall surface of NCs:

Active areas of different pore/NC designs

estimations are based on the assumptions of 1 cm^2 large and $10 \text{ }\mu\text{m}$ thick foils each, with 5×10^7 pores/ cm^2 of cylindrical shape with $1 \text{ }\mu\text{m}$ diameter, and with a close packing of TiO_2 nanoparticles with 50 nm diameter on the whole foil surface.

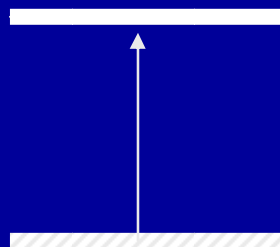
Membrane Arrangement	Massive TiO_2 membrane	TiO_2 fibrilles on a supporting foil	TiO_2 nanoparticles adsorbed to surfaces of microporous foil
Overall photoactive TiO_2 area [cm^2]	2	15.4	40.6
			

Gas & Water purification by photocatalysis

Destruction of - virusses, bacteriae, fungi, algae
- ethylene gas (= aging hormone)

candidates

TiO₂,
 ZnO,
 SnO₂,
 CaTiO₃,
 Fe₂O₃,
 MoO₂,
 MoS₂,
 NbO₅,
 CdS,
 KNbO₃,
 SrTiO₃,
 CdSe,
 CdS,
 WO₃,
 Ti_xZr_{1-x}O₂,
 SiC



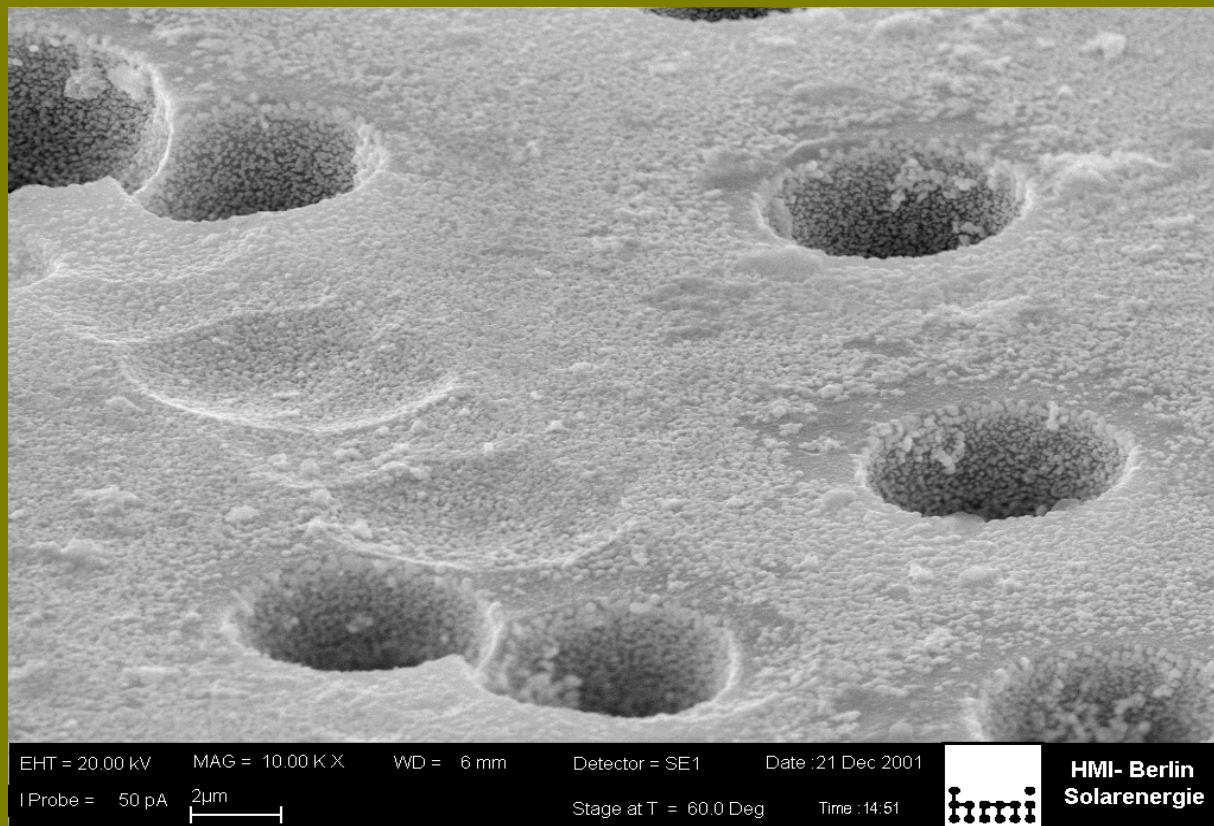
Band gap 3.2 eV

--> $\lambda < 390 \text{ nm}$

Preferential

Phase: Anatase

Holes diffuse to surface, react with adsorbed H₂O,
 form there OH⁻ and H₂O₂ radicals --> atomic O
 As $E_{\text{pot}}(\text{radicals}) > E_{\text{bond}}(\text{organics})$ --> destruction



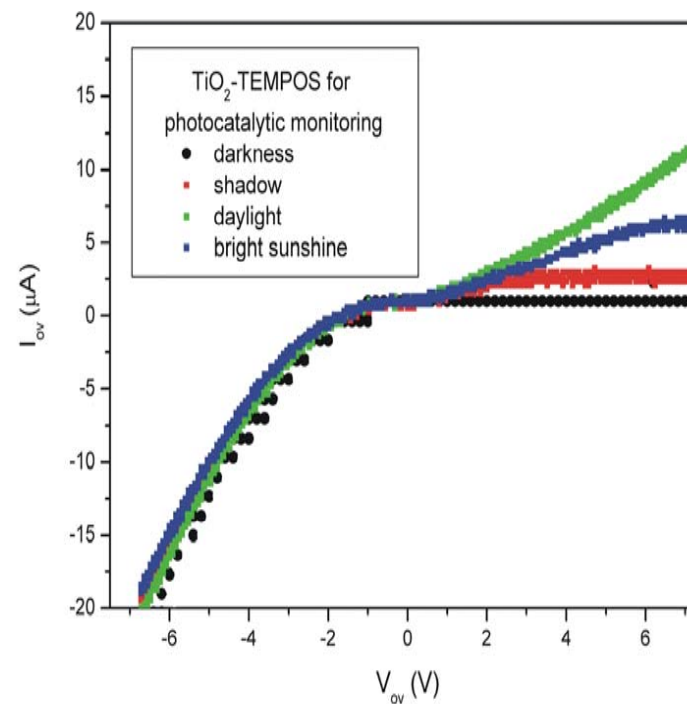
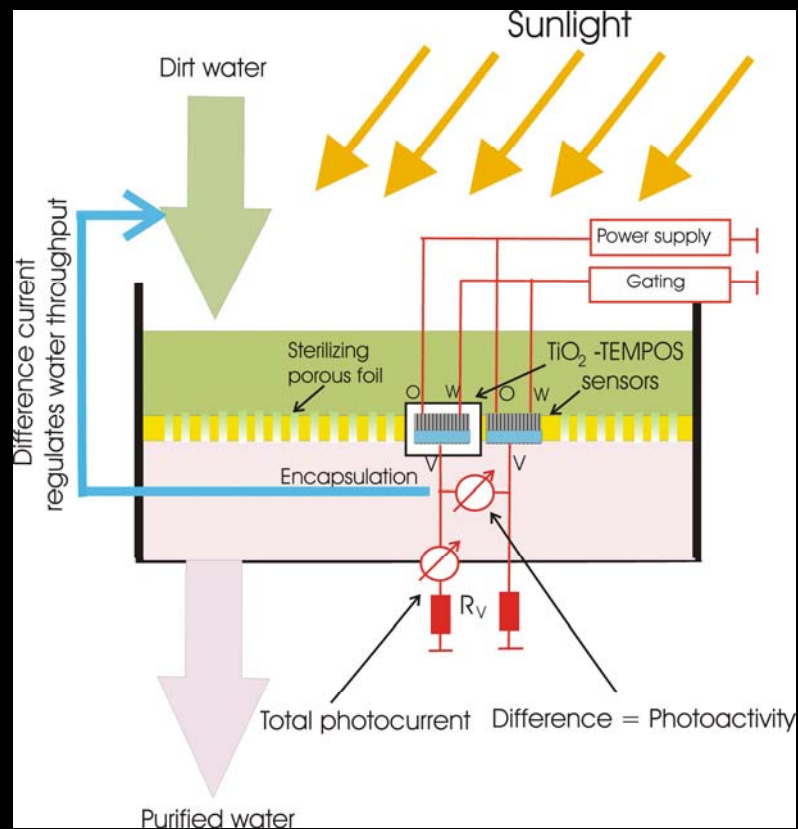
TiO₂ nanoparticles on Ag tubules in track; PI matrix
What can be seen are not the nanoparticles, but clusters of them
(nanoparticle diameter: 20 nm)

Food sterilization with TiO_2 -track-foil



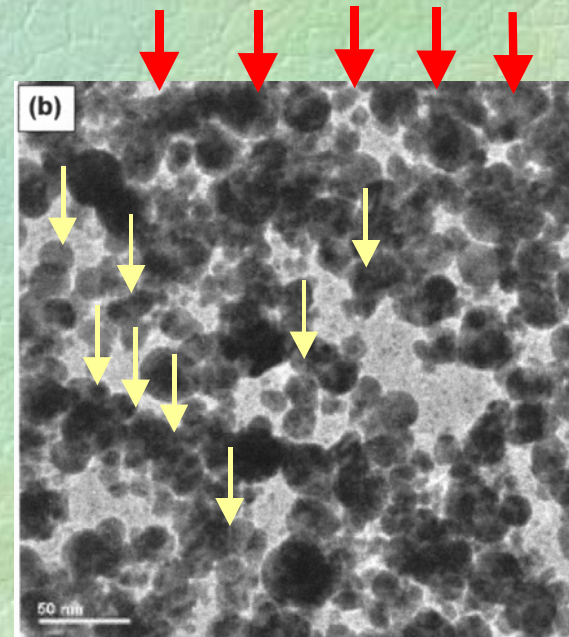
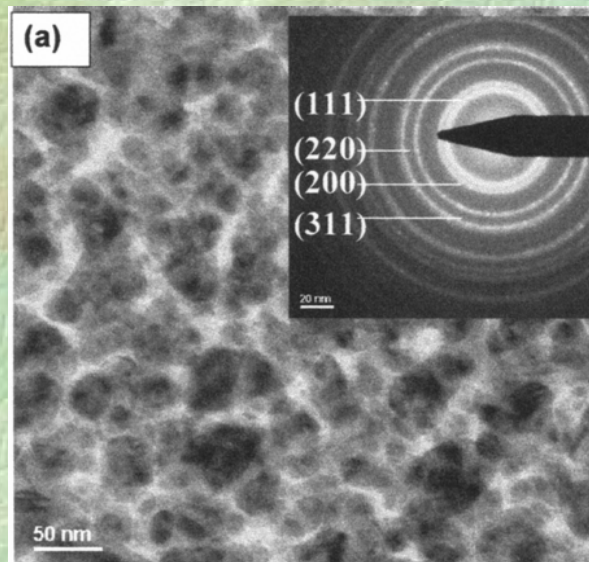
Intelligent solar water purification system

Anatase sensor records the photocatalytical activity of anatase



Nanocluster architecture: nanowire formation by SHI irradiation

Biswas et al. 2002/2003:
120 MeV Au $\rightarrow$ Au/Teflon AF



alignment of Au clusters along the ion tracks

Macroscopic properties of dispersed conducting nanoclusters: tailoring of conductivity

Bulk metal



metallic conductivity (Ohmic)

touching clusters



percolation (*grain boundaries*)

small distance



tunneling (*quantum physics*)

larger distances



Schottky emission (*thermal*)

larger distances



field emission (*high fields*)

contaminants, moisture →

ionic conductivity

Basic conduction mechanism in insulators

for a supposed MIS (metal-insulator-semiconductor) arrangement.

Process Name	Description
Schottky emission	Thermionic emission
Frenkel-Poole emission	Field-enhanced thermal excitation of trapped electrons into the conduction band
Tunnel or field emission	Field ionization of trapped electrons into the conduction band, or by electron tunneling from the metal Fermi energy into the insulator conduction band
Space-charge limited current	carrier injection into the insulator, where no compensating charge is present
Poole-Frenkel, Gill	Current is carried by thermally excited electrons hopping from one isolated state to the next
Ohmic conduction	Migration of electrons
Ionic conduction	Diffusion of ionic charge carriers

From: S.M.Sze, Physics of semiconductor devices. John Wiley & Sons, 1981

Quantitative relations for various conduction mechanisms

Process	Voltage and temperature dependence
Schottky emission	$\sim T^2 \exp(c_1 \sqrt{V/T} - c_2/T)$
Frenkel-Poole emission	$\sim V \exp(2c_1 \sqrt{V/T} - c_2/T)$
Tunnel or field emission	$\sim V^2 \exp(-c_3/V)$; temperature indep.
Space-charge limited current	$\sim V^2$; temperature indep.
Poole-Frenkel, Gill	$\sim \exp(V^{1/2} / T)$
Ohmic conduction	$\sim V \exp(c_4/T)$
Ionic conduction	$\sim V \exp(c_4/T)$

The c_i are coefficients containing information about the barrier height, insulator dynamic permittivity, effective charge carrier mass, insulator thickness, and/or the activation energy of the charge carriers, respectively.

From: S.M.Sze, Physics of semiconductor devices. John Wiley & Sons, 1981

Tailoring of nanowire properties by aligning (semi)conducting nanoclusters along latent or etched tracks

A possible recipe:

Bring nanoparticles into solution as colloides by attaching to them hydrophile ligands, let the solution dry within the tracks

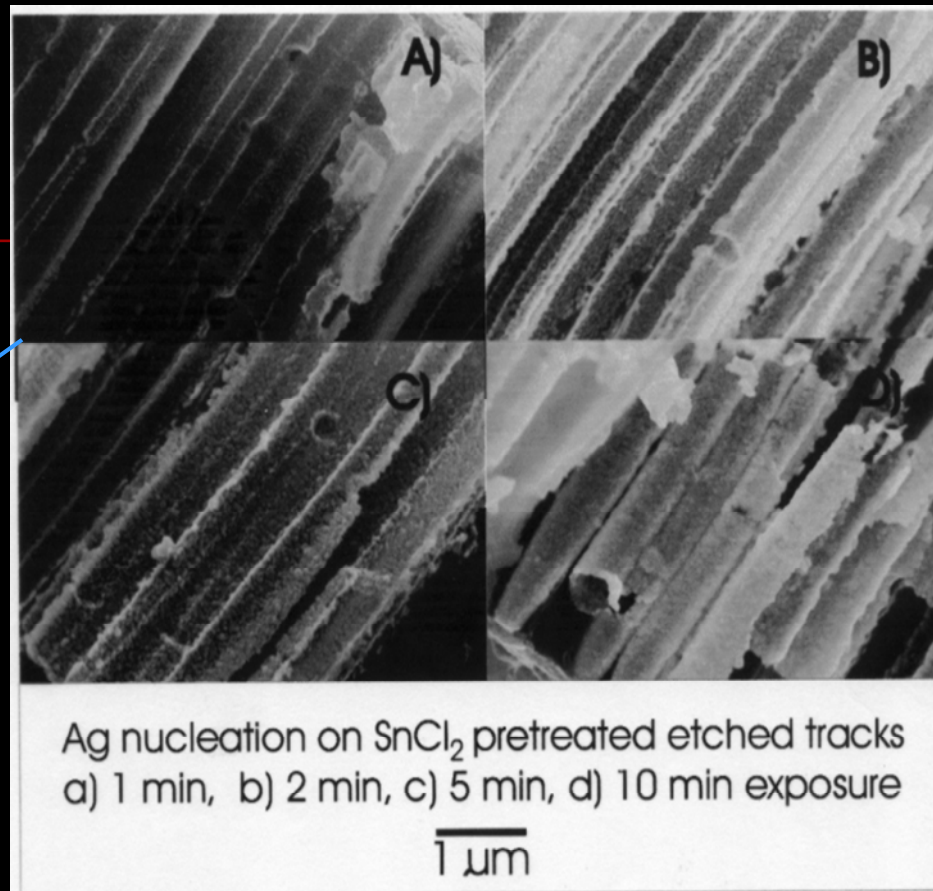
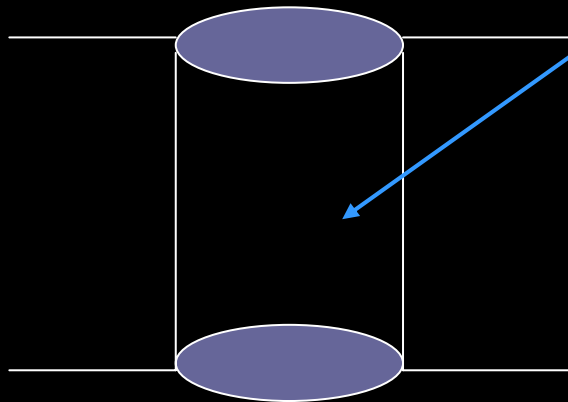
Other recipe:

let a solid precipitate from solution at preferred nucleation centers; interrupt the precipitation process in a very early stage

Examples verified by us:

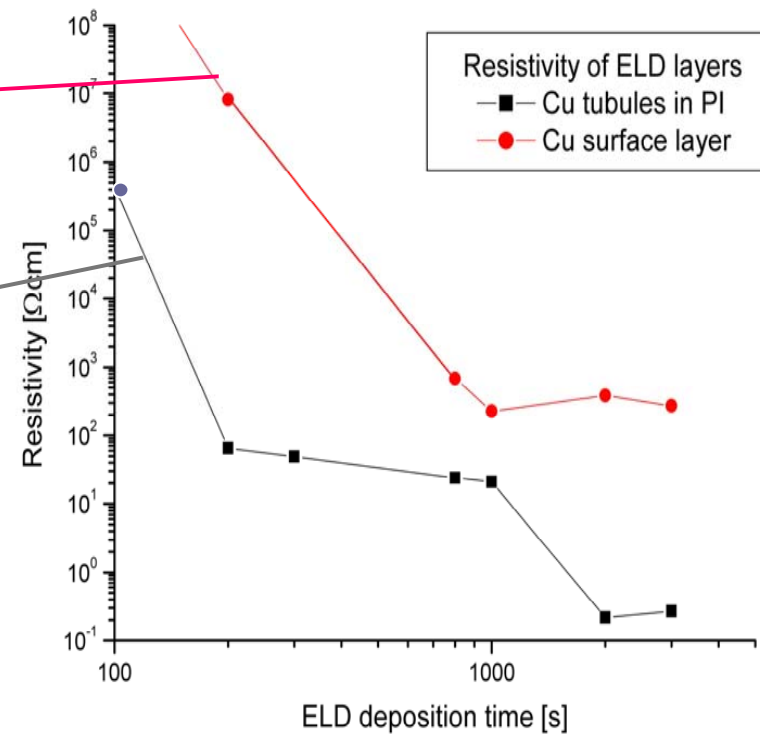
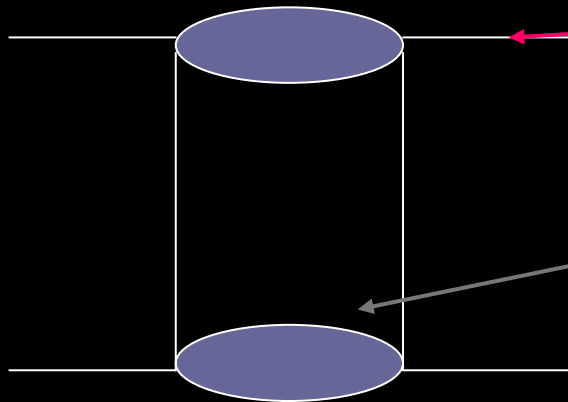
LiNbO₃, SiO₂, TiO₂, Cu, Ag, Au, Ni, Pd, CdS, PbS, ...

Time dependence of chemical deposition of Ag

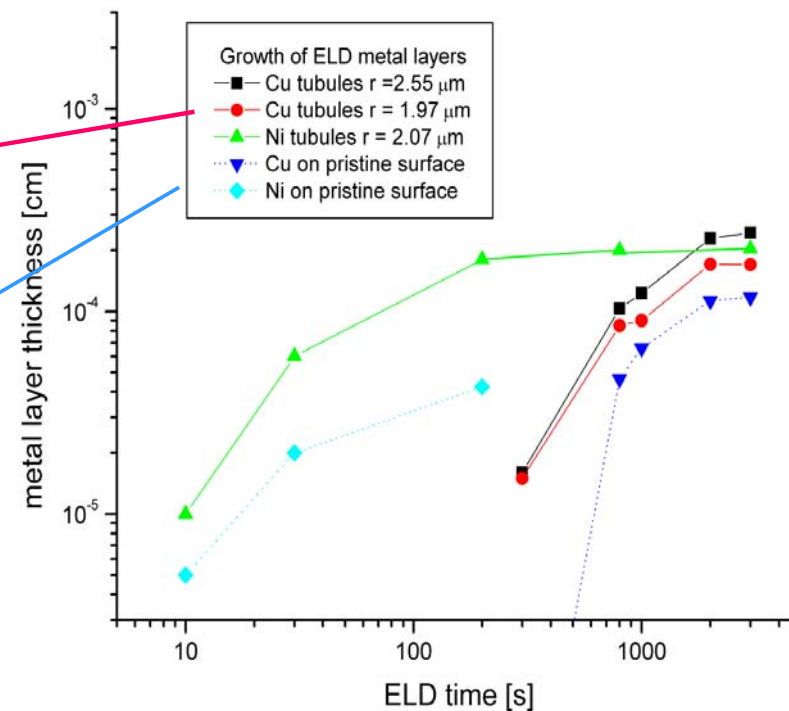
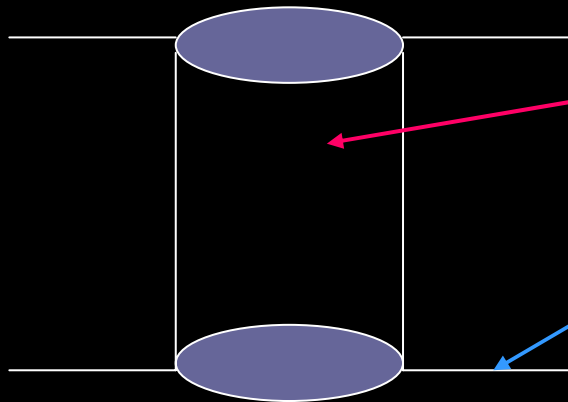


- | | | |
|----------|---|-------------------|
| A | first deposition on nucleation centers | < 10 nm |
| B | monolayer of metallic clusters | ~ 20 nm |
| C | clusters touch each other | ~ 50 nm |
| D | mechanically stable tubule | > 50 nm |

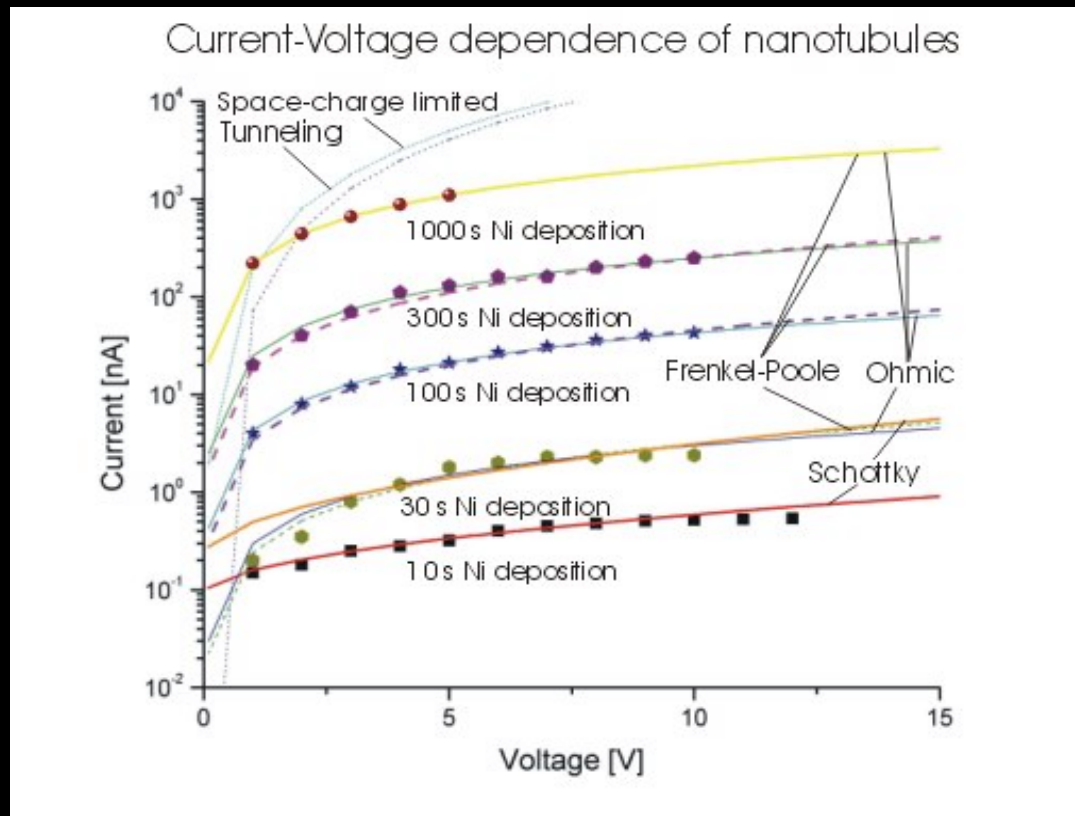
Time dependence of chemical deposition of Cu nanoclusters



Time dependence of chemical deposition of Cu and Ni nanoclusters



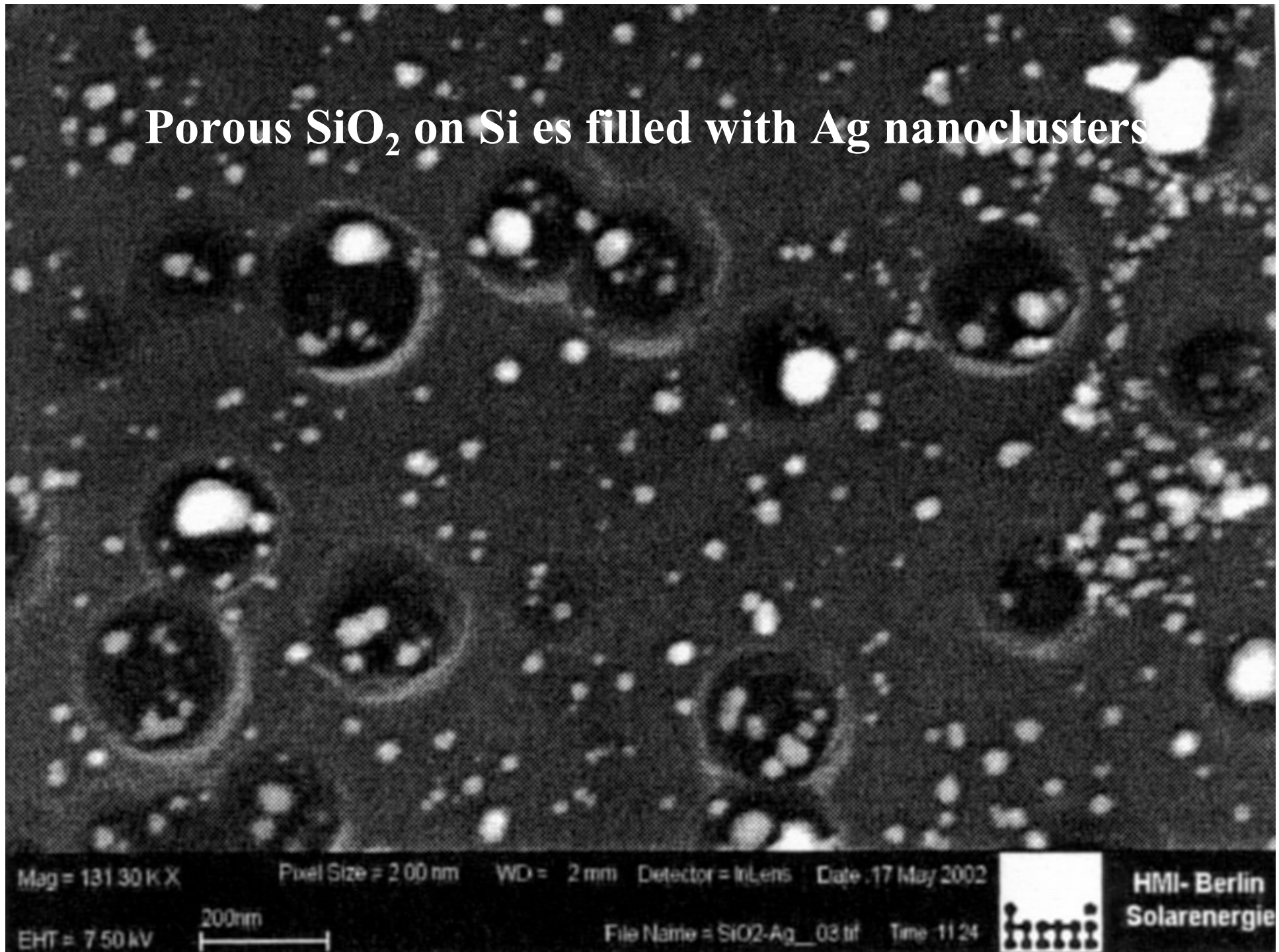
Current/voltage relations

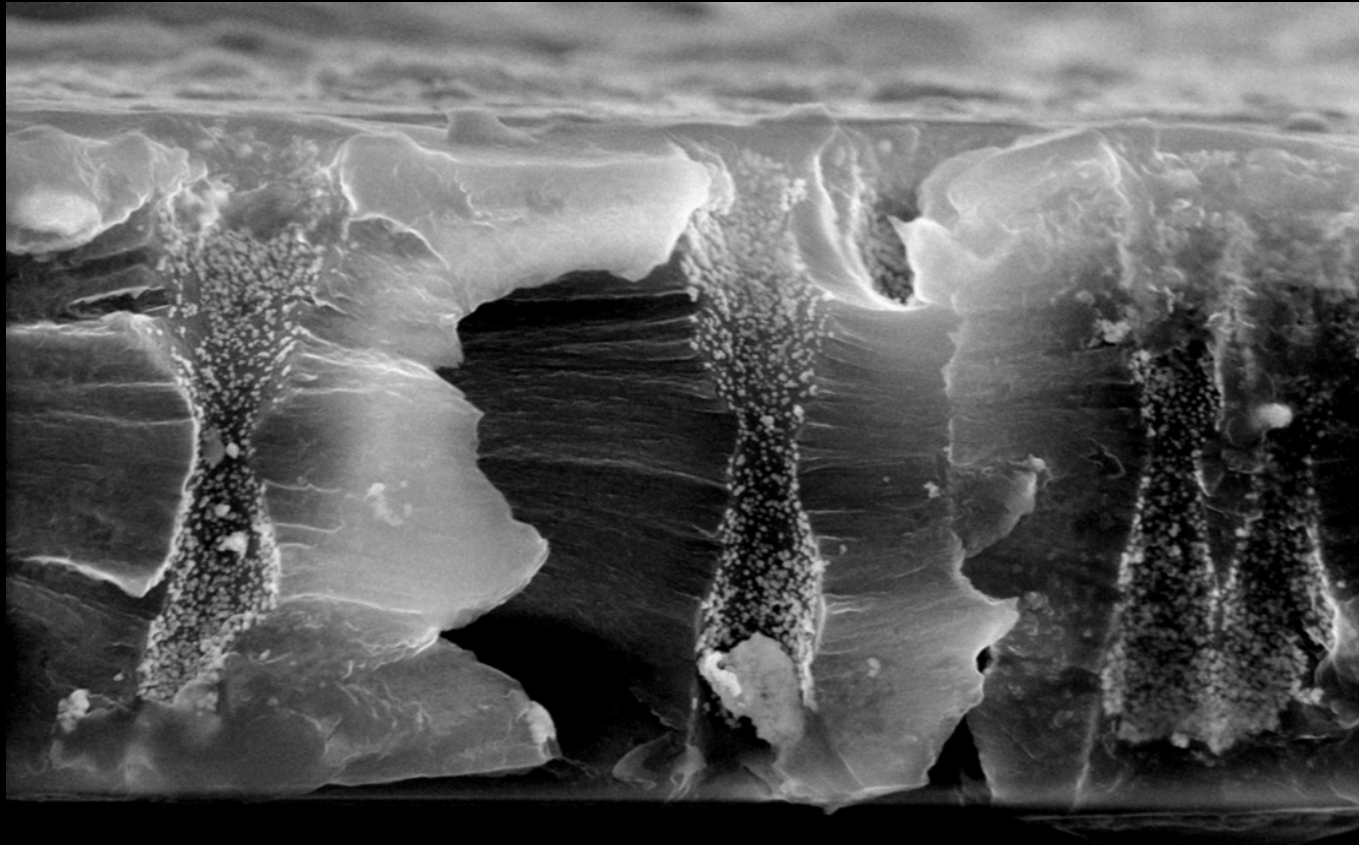


The current/voltage characteristics of Ni-filled microporous PET foils, as compared with several conduction theories. Conductivity values measured along the ion track directions (i.e. through the foils).

10 s: Schottky emission
≥ 30 s: Ohmic conduction

Porous SiO_2 on Si es filled with Ag nanoclusters





EHT = 20.00 kV MAG = 8.77 K X WD = 9 mm

Detector = SE1 Date : 19 Feb 2002

I Probe = 200 pA 2µm

Stage at T = 80.0 Deg Time : 16:18



HMI- Bei
Solarene

Ag nanoclusters in etched tracks in polyimide

Important: the role of nucleation centers

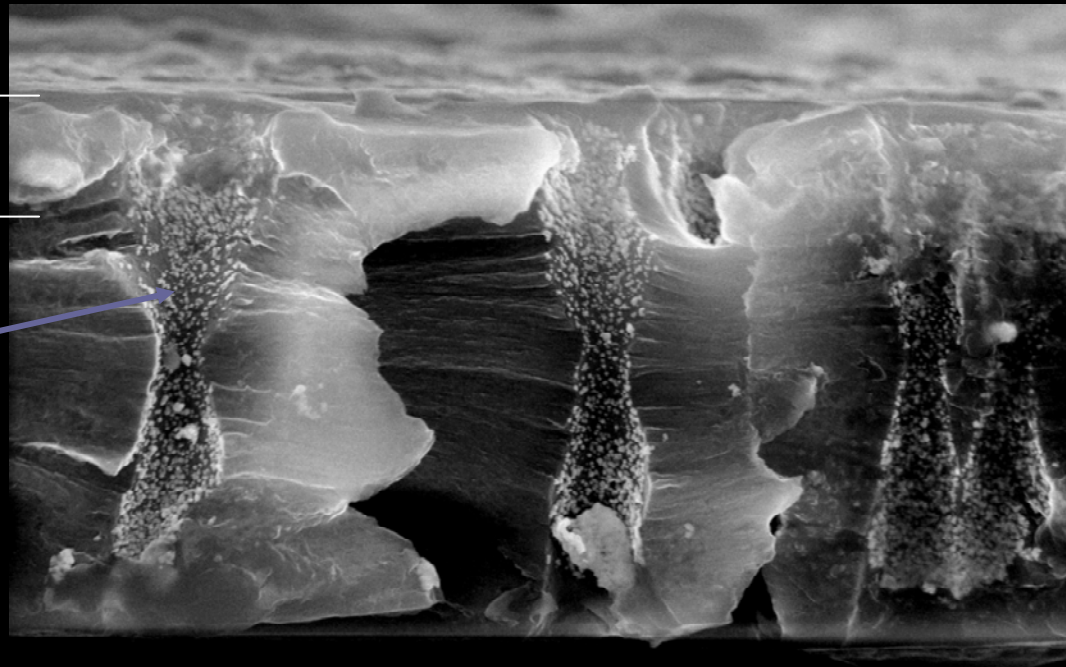
Nucleation center formation by physics or chemistry

mechanical, Laser, energetic ion irradiation

metal atoms bond to substrate

Ion range

*Intrinsic defects
act as nucleation
centers*



EHT = 20.00 kV MAG = 8.77 K X WD = 9 mm
IProbe = 200 pA 2µm

Detector = SE1 Date : 19 Feb 2002
Stage at T = 80.0 Deg Time : 10:18



HMI- Be
Solarene

Nanoparticle architecture: tailoring of nanocluster parameters

Distribution

in case of nucleation center formation by ion irradiation:

Ion beam position

density

deposited energy density

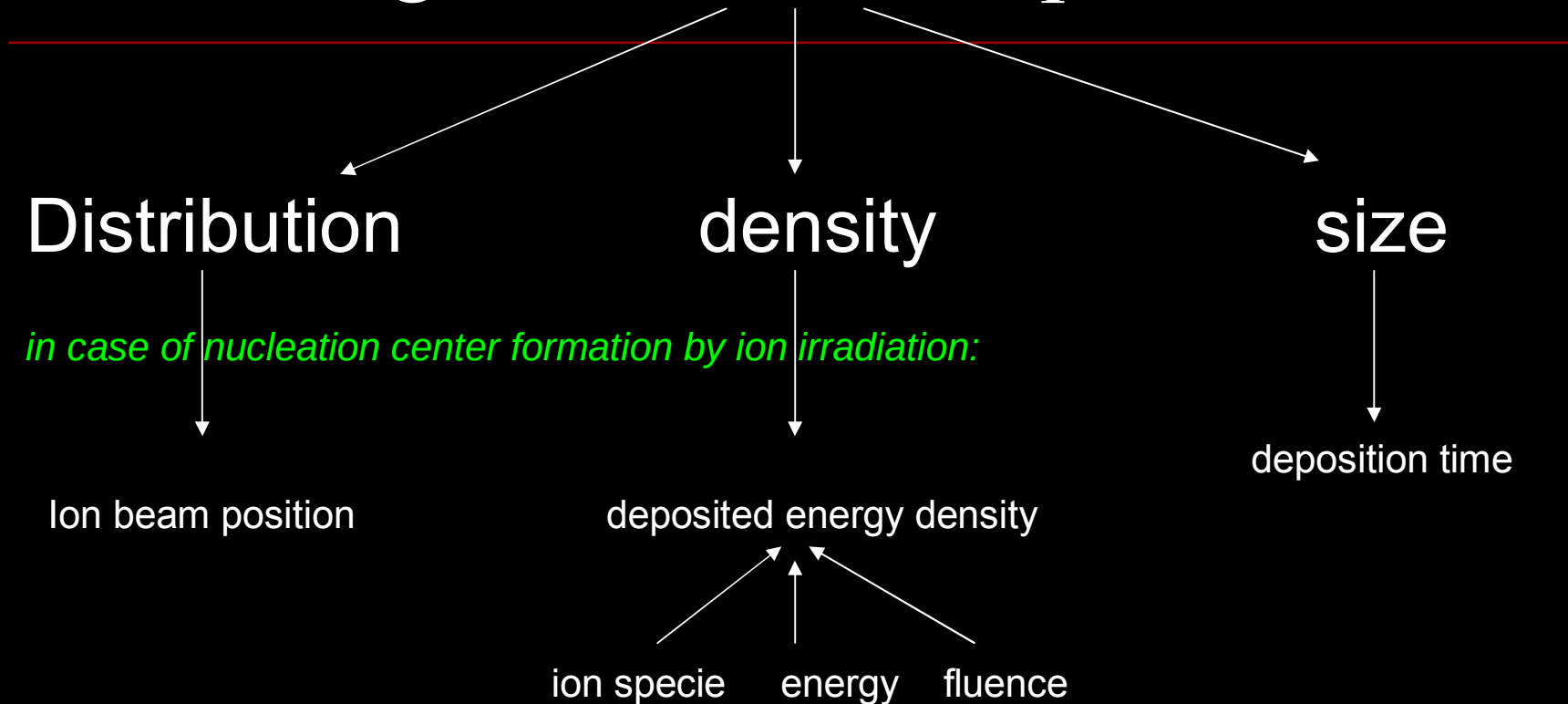
ion specie

energy

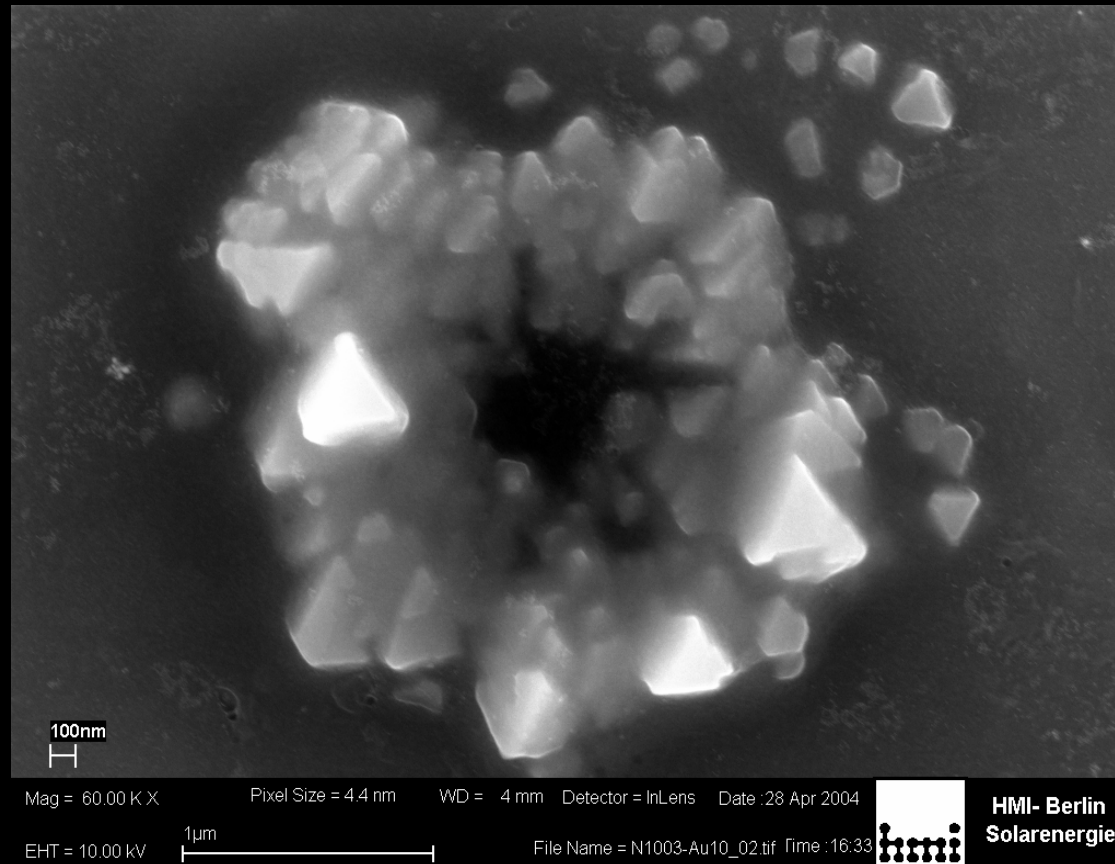
fluence

size

deposition time

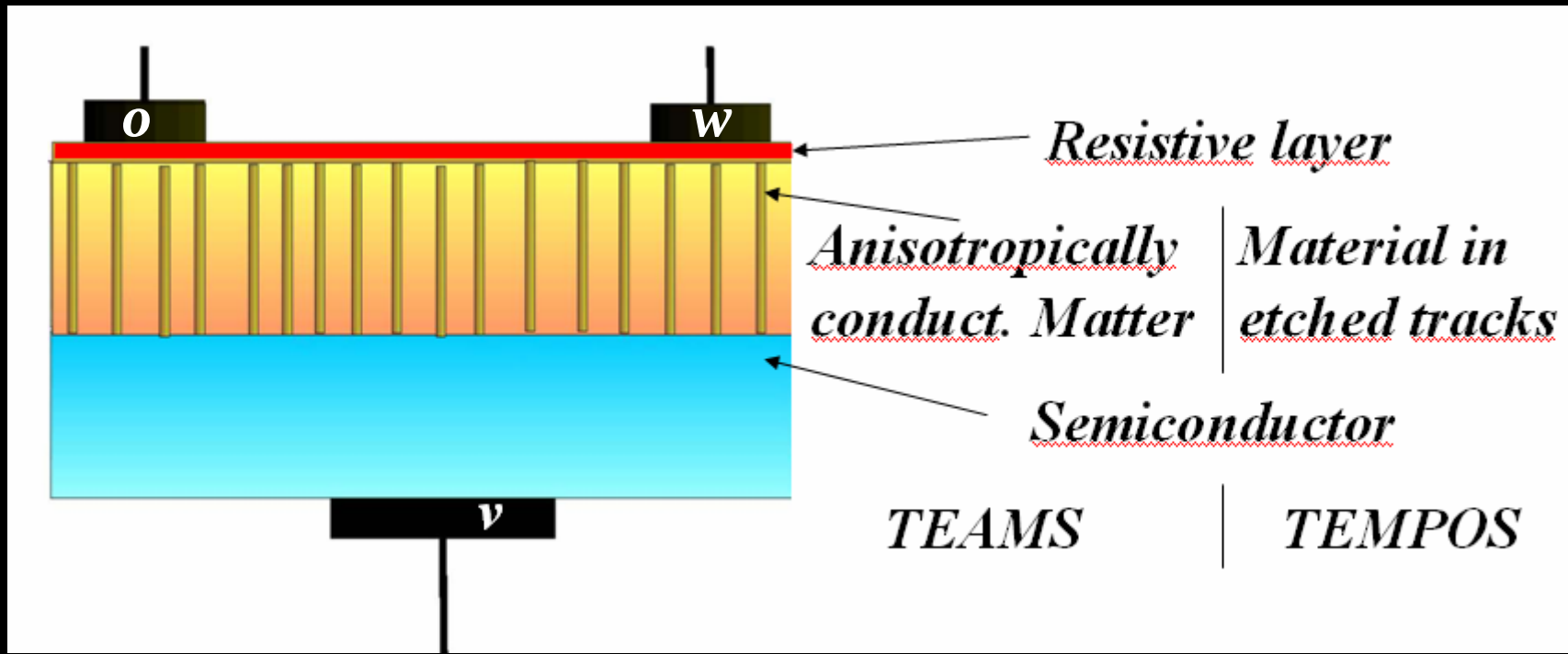


Au nanoparticles in etched tracks: Formation of tetrahedral superstructures

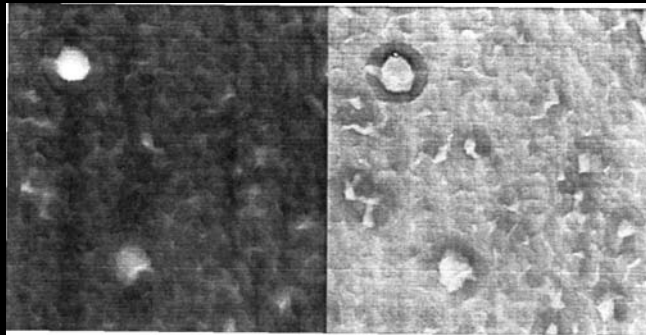


Tuneable Electronically Anisotropical Material on Silicon (TEAMS)

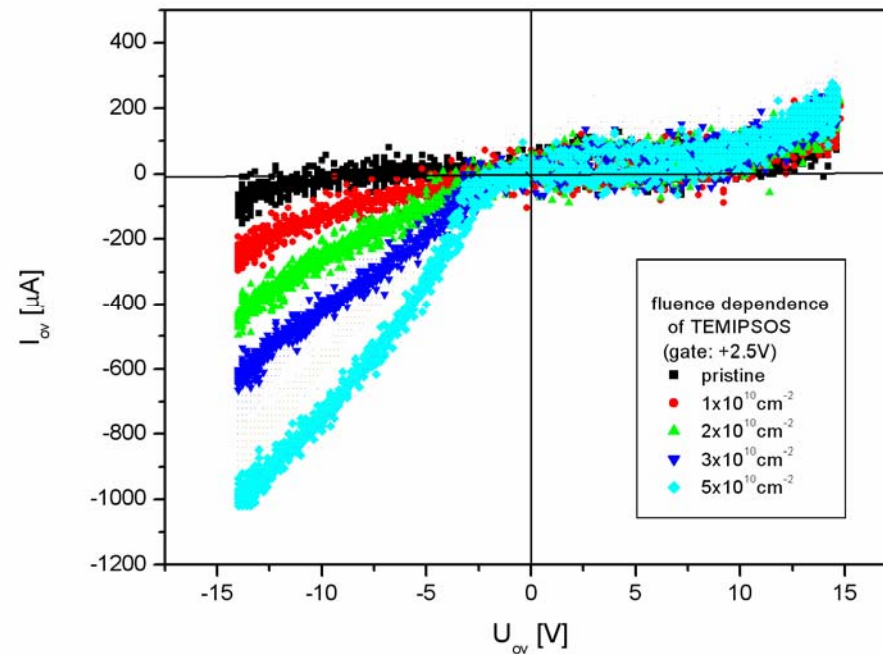
Tunable Electronic Material with Pores in Oxide on Silicon (TEMPOS)



Example of an in-situ measurement: Polysilane-TEAMS (350 MeV $^{197}\text{Au}^{26+}$ at ISL,HMI Berlin)



*The creation of SiC
nanorods along the
ion tracks changes the
I/V characteristics*

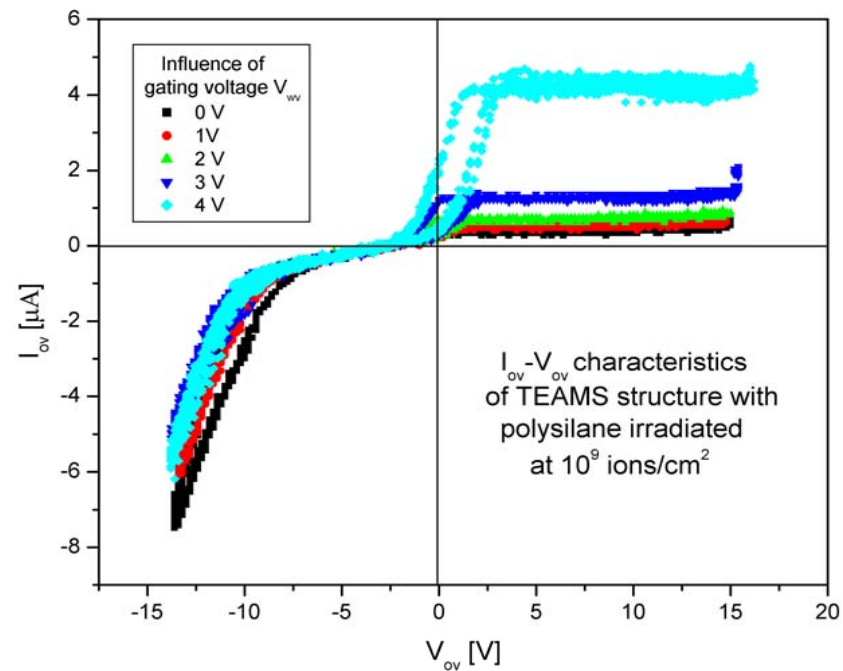


Result:

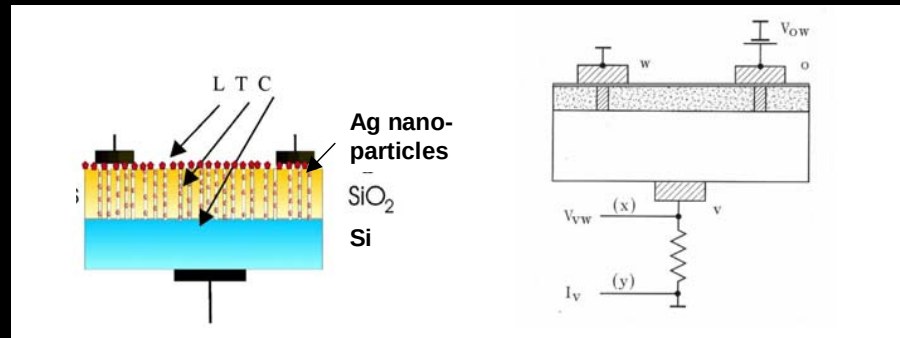
GATING VOLTAGE DEPENDENCE OF POYLSILANE-TEAMS

PECULIARITIES:

Transistor-like gating in
1st quadrant,
diode dependence in
3rd quadrant,
hysteresis near the origin

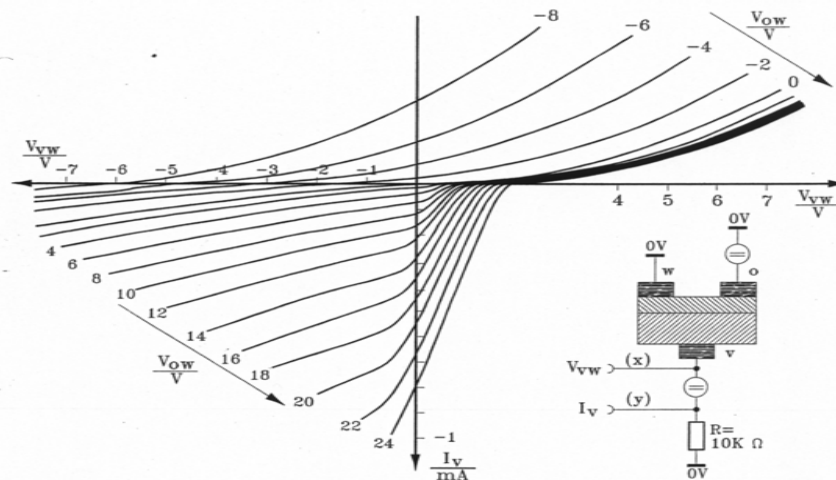


Example: TEMPOS structures



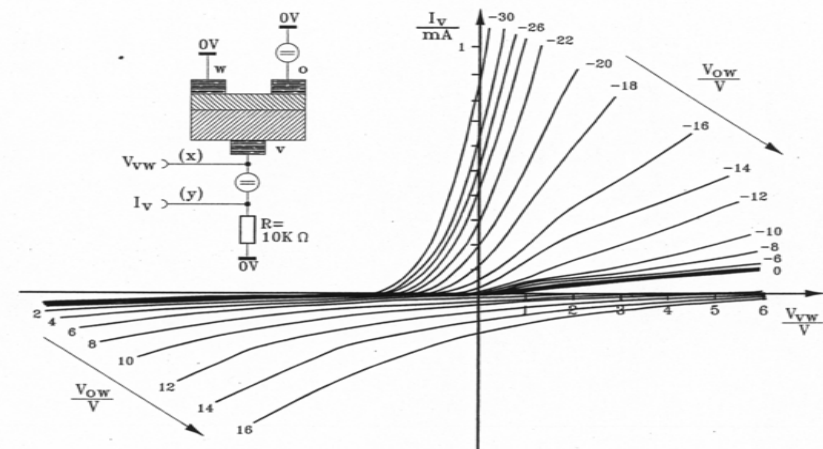
I-V characteristics (overview)

Type 1



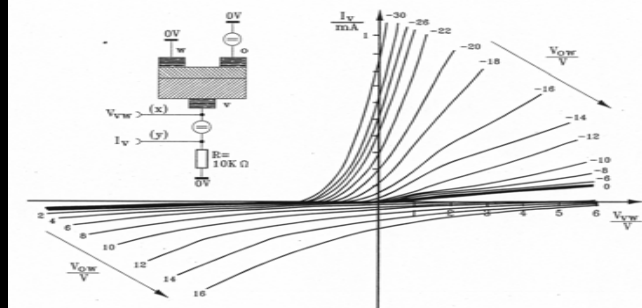
I-V characteristics (overview)

Type 2



I-V characteristics (overview)

Type 2



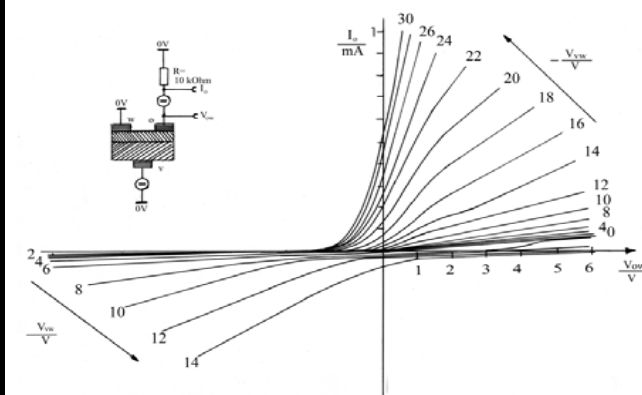
$$I_v(V_{vw})$$

$$I_o(V_{ow})$$

$$I_o(V_{ov})$$

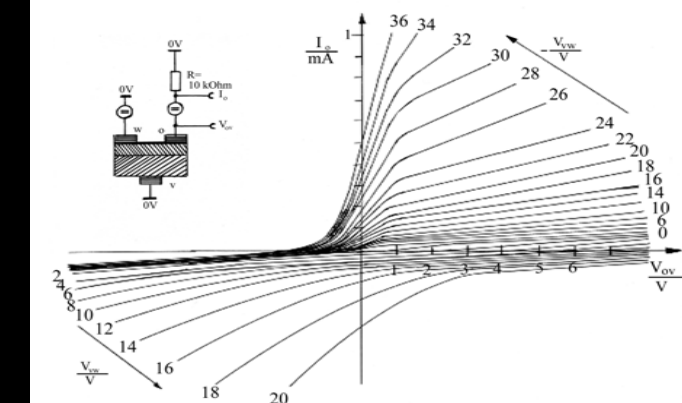
I-V characteristics (overview)

Type 2

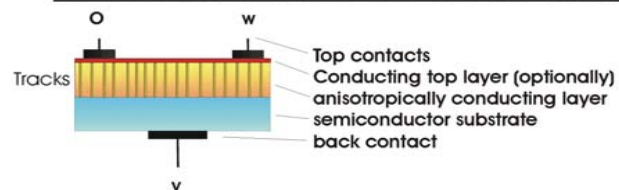


I-V characteristics (overview)

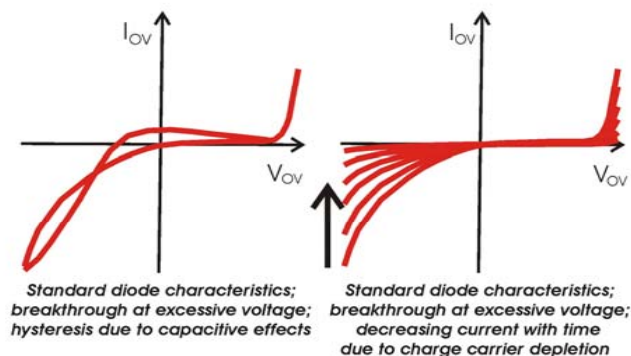
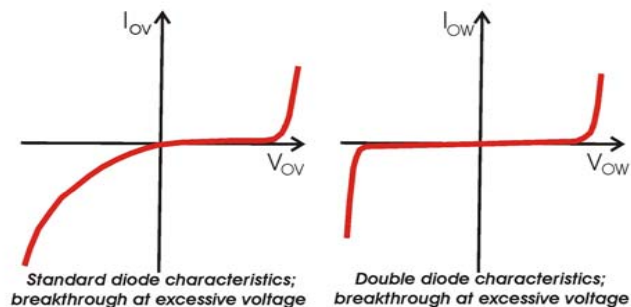
Type 2



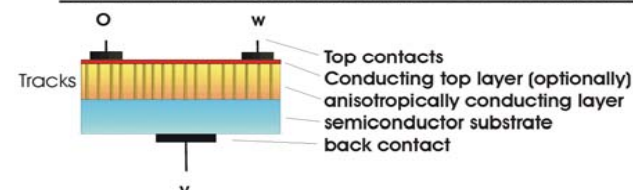
Schematic current/voltage characteristics of TEAMS and TEMPOS structures



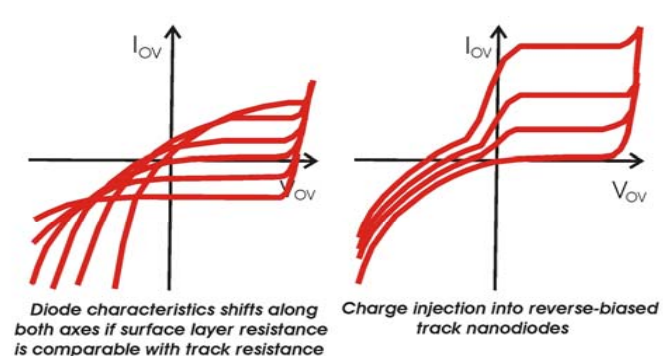
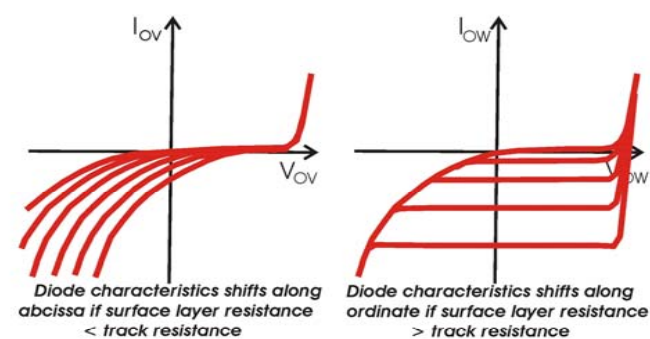
2 contacts active, 3rd contact dangling

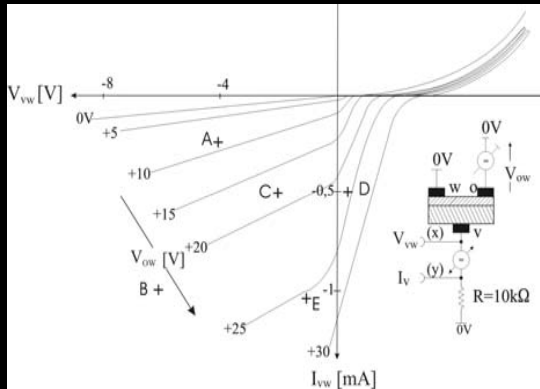


Schematic current/voltage characteristics of TEAMS and TEMPOS structures



Dependence of source-drain (o-v) current on gate (w) voltage

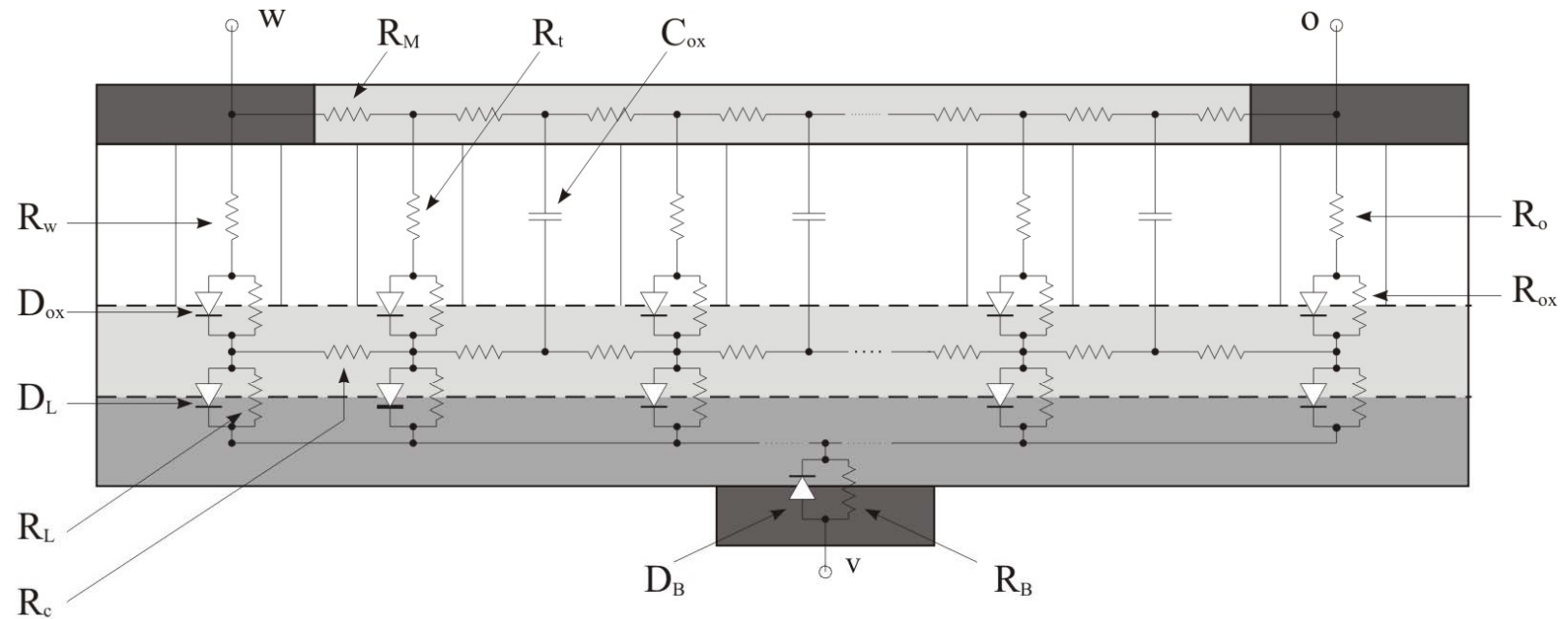




Transistor properties at some operating points

Measurement point	A $V_{vw} = -4 \text{ V}$ $I_v = -0.2 \text{ mA}$	B $V_{vw} = -6 \text{ V}$ $I_v = -1.0 \text{ mA}$	C $V_{vw} = -2 \text{ V}$ $I_v = -0.6 \text{ mA}$	D $V_{vw} = 0.5 \text{ V}$ $I_v = -0.5 \text{ mA}$	E $V_{vw} = -1 \text{ V}$ $I_v = -1.1 \text{ mA}$
M_p					
Common emitter	0.18	1.17	0.64	0.054	0.053
common base	0.4	0.12	0.04	0.64	1.12
common collector	0.05	24	0.034	0.017	0.074

Equivalent circuit for TEMPOS



Theoretical approach to TEMPOS

- * Calculate voltages V along tracks, resistive surface coating, and channel

--> get drain current by differentiation:

$$I_o = \int j(x,y) dx dz = W \mu (-dV_c/dy) \int n(x,y) dx$$

(integral is surface charge density $\sigma(y)$)

related to oxide field by: $\sigma(y) = \epsilon_{ox} E_{ox}$

- * with $E_{ox} = \Delta V/d_{ox}$ --> calculate ΔV

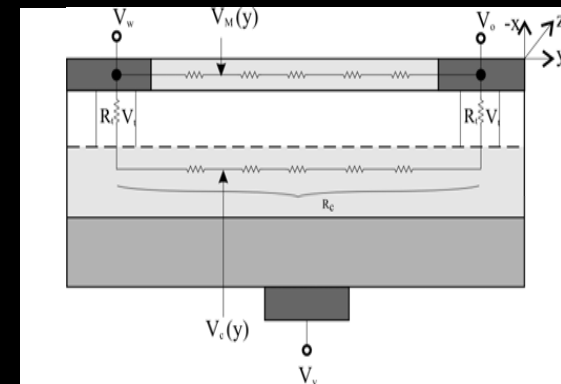
- * insertion, integration -->

$$I_o = \beta (R/(R+2) (V_v + V_w) (V_o - V_w))$$

$$\text{with: } \beta = C_{ox} \mu W/L$$

valid for small V_{ow} , else prevailing field effect

--> approaches to classical MOS transistor

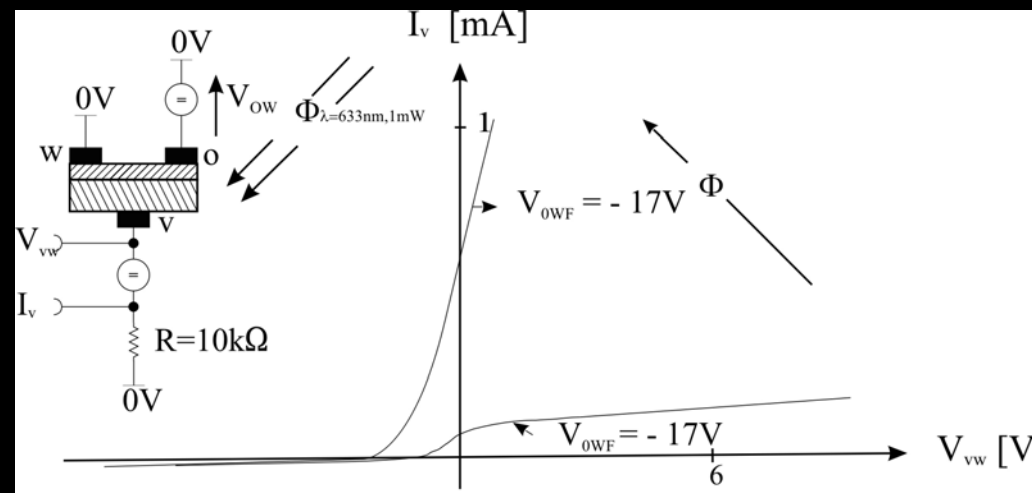


TEAMS & TEMPOS sensors

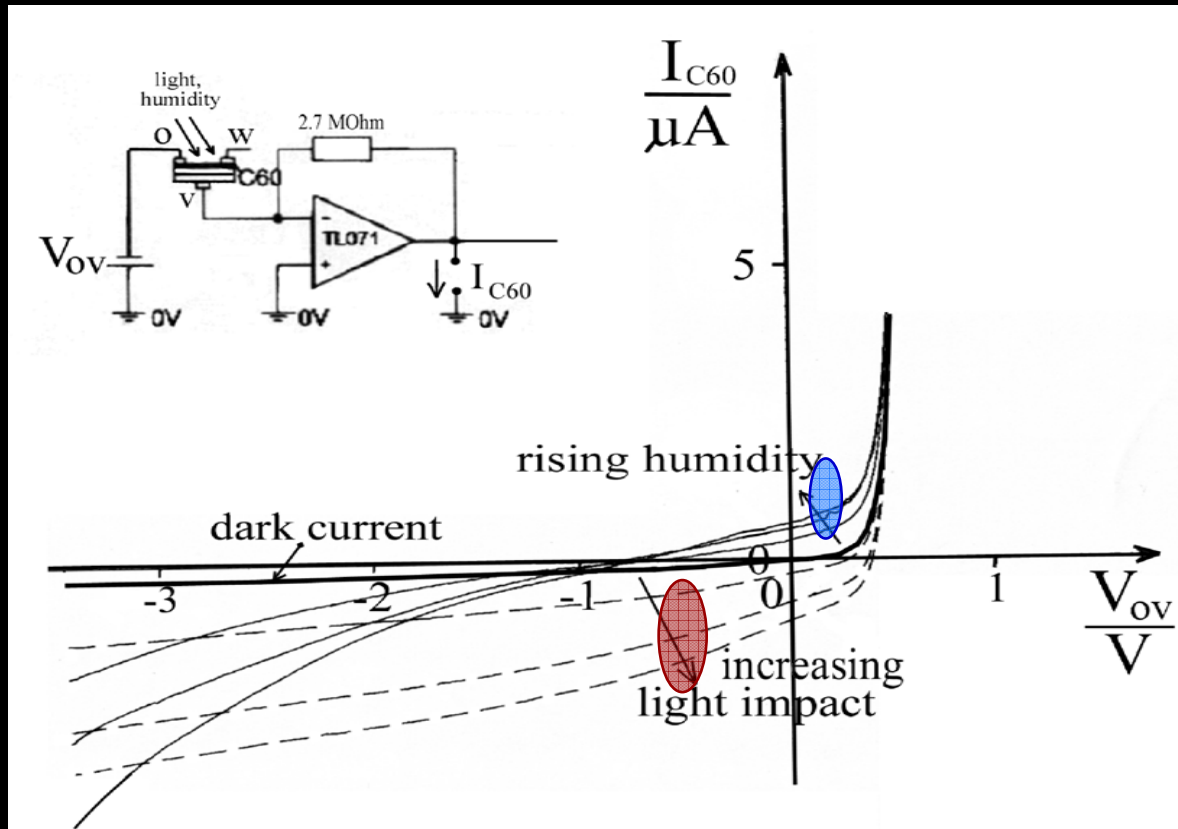
There are some intrinsic physical properties which enable the TEAMS & TEMPOS structures to act as a sensor.

Example: *light sensitivity.*

Application of a light source shifts the characteristic from a low conductive state to a high conductive one due to increase in carrier concentration in space charge region



Humidity sensing with TEMPOS



Si/SiO₂(C₆₀):

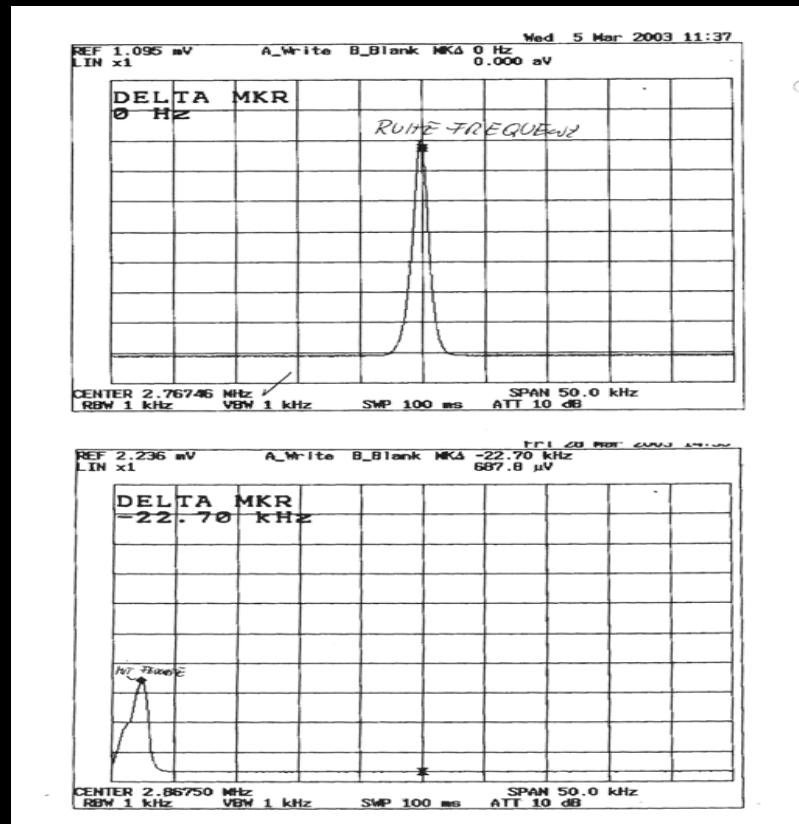
Humidity:

I_v increases

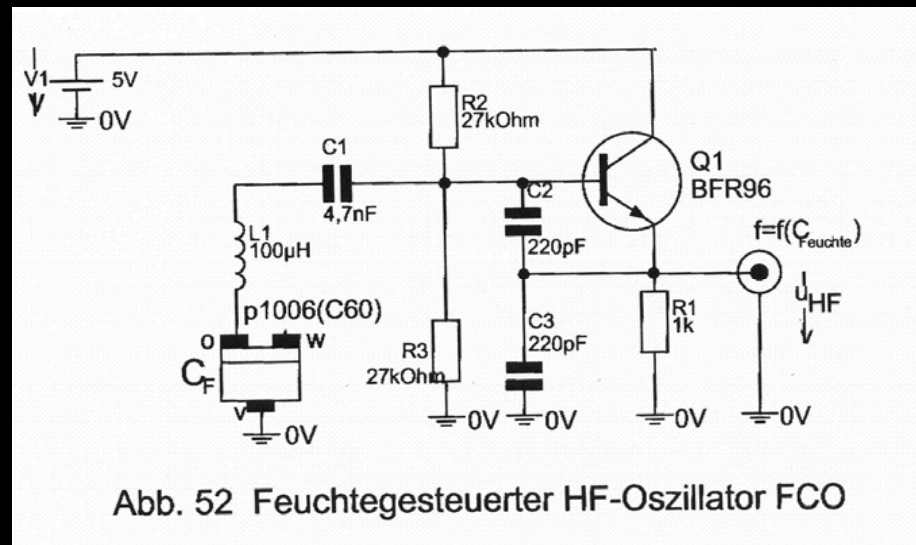
Light, alcohol:

I_v decreases

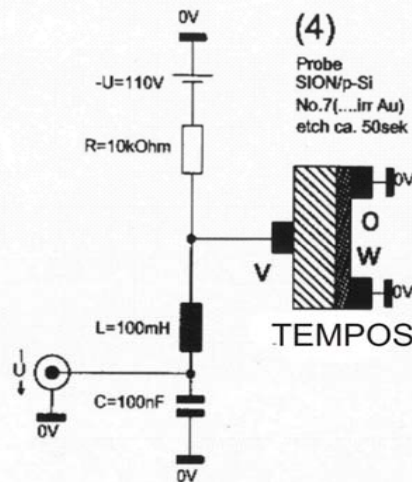
Humidity sensing with TEMPOS:



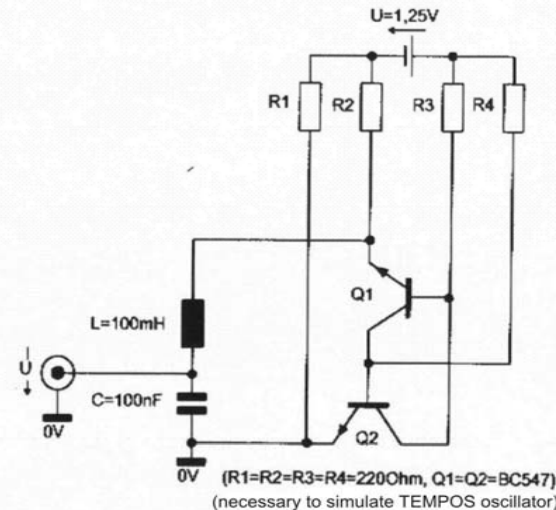
*Sensitive humidity recording
by frequency measurement*



Comparison of transistor electronics and SITE



TEMPOS oscillator
simple, 4 elements only



Transistor oscillator
more complicated, 8 elements necessary

The internal complexity of TEMPOS leads to simplified circuits.
→ easier and cheaper circuits than with conventional transistor technology; faster electronics.

A common feature for SITE:
Negative differential resistances (NDR)

NDRs can have two origins:

- **Instabilities in individual entities (traps, tracks)**
- **Collective track-track interactions**

In spite of different mechanisms, both effects
lead to similar effects

First hints for NDRs in pores from biology ~ 1970

Current-Voltage relationship of the electrogenic pump in *Acetabularia mediterranea*. by: D.Gradmann, W.Klemke in: Membrane Transport in Plants, U.Zimmermann and J.Dainty eds., Springer 1974, p.131-138

Also frequent pore effects:
Pulsating current in latent tracks in PET
(Correlation with NDRs?)

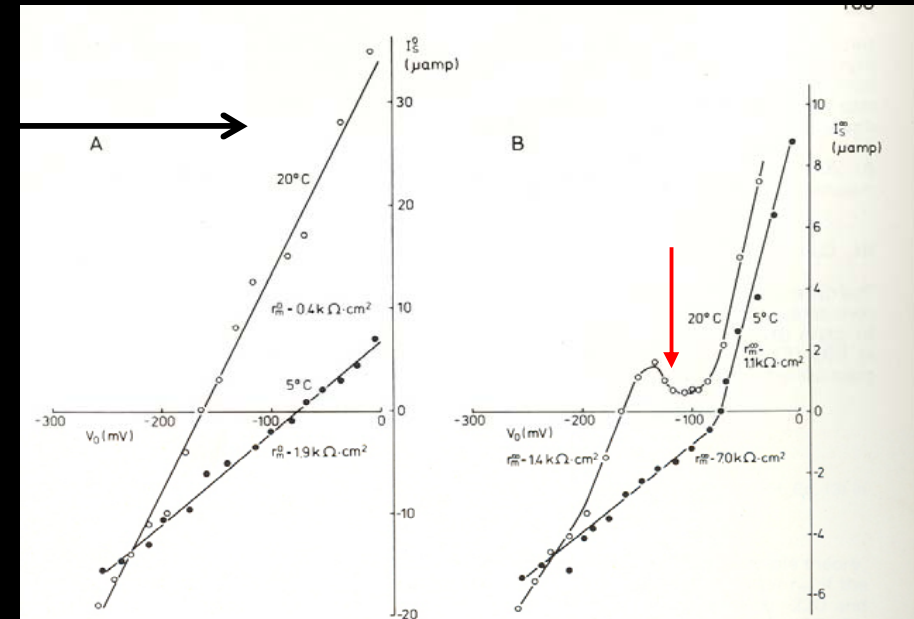
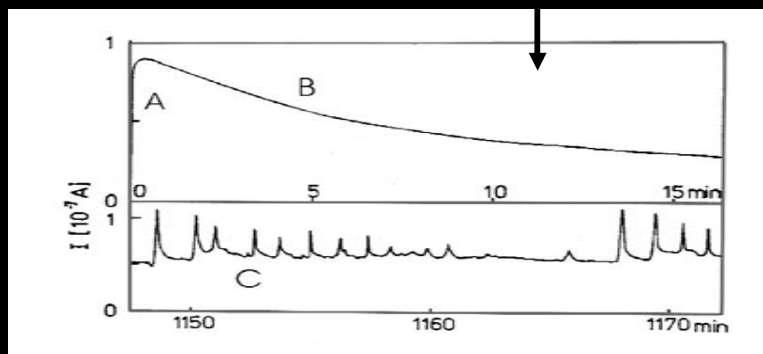


Fig. 2. A, early; B, steady state voltage clamp input I—V relationship. Recording from one cell in darkness at 20°C (○—○), and 5°C (●—●).

At 20°C, when the pump is operating, additional current passes through the pump channels. The most striking feature of the steady state I—V curve at 20°C is its N-shape under depolarisation; it finally merges with the high conductance potassium branch. This is certainly a rather complex phenomenon, since voltage- and space-dependent events in different pathways seem to be involved. At ~~the moment this question will not be pursued further.~~

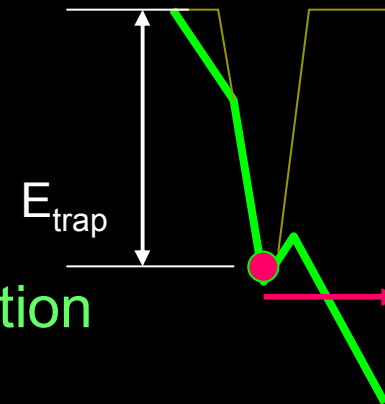
NDR of individual entities

(shown here for the example of deep traps)

Suppose -

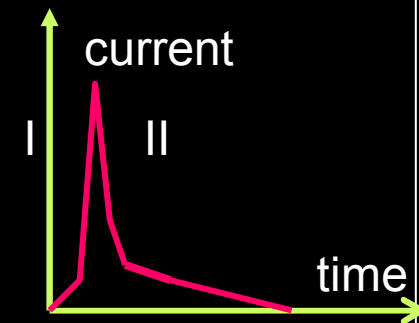
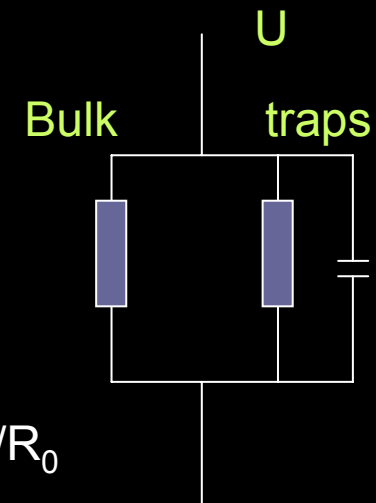
- deep traps are produced by irradiation of a material, e.g. SnO_2 in a TEAMS structure
 - these traps are filled by charge carriers
 - the sample is subject to a strong field gradient
- Then a slight trigger may release all charges simultaneously
- Strong “stimulated emission” current
- Breakdown of applied voltage
- Negative differential resistance

Permanent repetition of this game → pulsation



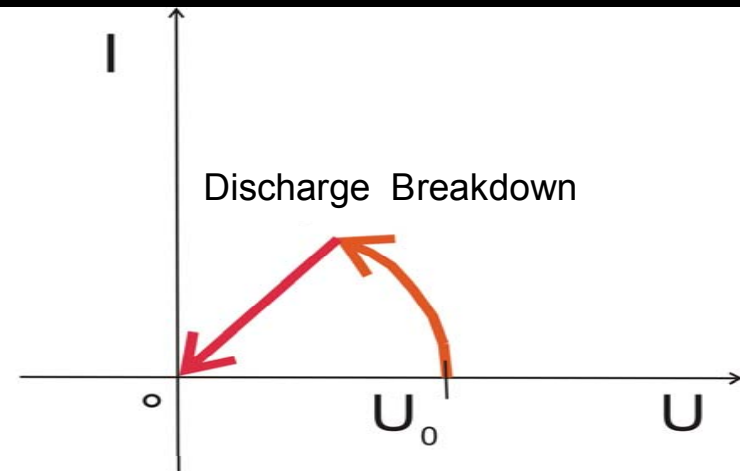
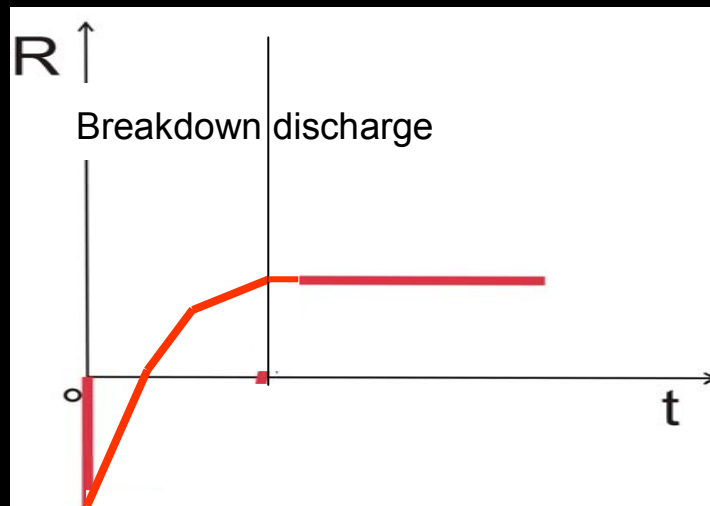
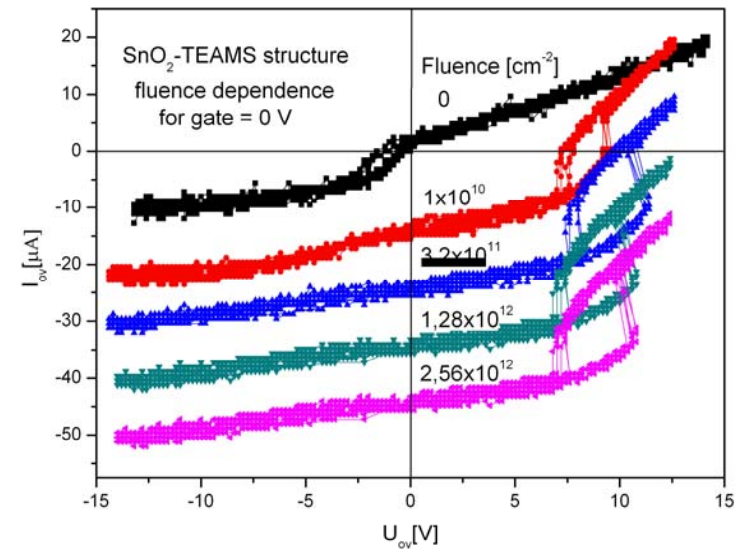
Theory of stimulated current emission from deep traps in tracks

- Total equivalent circuit = bulk branch + parallel trap branch
- Equivalent circuit for deep traps = parallel $R_{\text{trap}} + C_{\text{trap}}$ described by a macroscopic trap resistance R_0
- For $U < E_{\text{trap}}$: $R_{\text{trap}} \rightarrow \infty$; for $U > E_{\text{trap}}$: $R_{\text{trap}} \rightarrow R_0 \sim 0$
- In this case: discharge current $I_{\text{disch}} = -dQ/dt = -C_{\text{trap}} dU/dt = U/R_0$ (adds to I_{bulk})
 - $Q/C_{\text{trap}} = R_0 dQ/dt \rightarrow Q = C_{\text{trap}} U_0 \exp(-t/(R_0 C_{\text{trap}}))$
 - $I_{\text{disch}} = dQ/dt = C_{\text{trap}} U_0 / (R_0 C_{\text{trap}}) \exp(-t/(R_0 C_{\text{trap}}))$
 - Voltage drop $\Delta U = \Delta Q / C_{\text{trap}} = U_0 / (R_0 C_{\text{trap}}) \exp(-t/(R_0 C_{\text{trap}}))$
 - $R_{\text{eff}}(t) = (U_0 - \Delta U(t)) / I = R_0 - f \exp(-t/(R_0 C_{\text{trap}}))$
 - Phase I (pulse buildup): negative trap resistance
 - Phase II (pulse discharge): trap resistance becomes positive → saturation



NDR of SnO_2 -TEAMS

evolution of the discharge pulse, schematic:



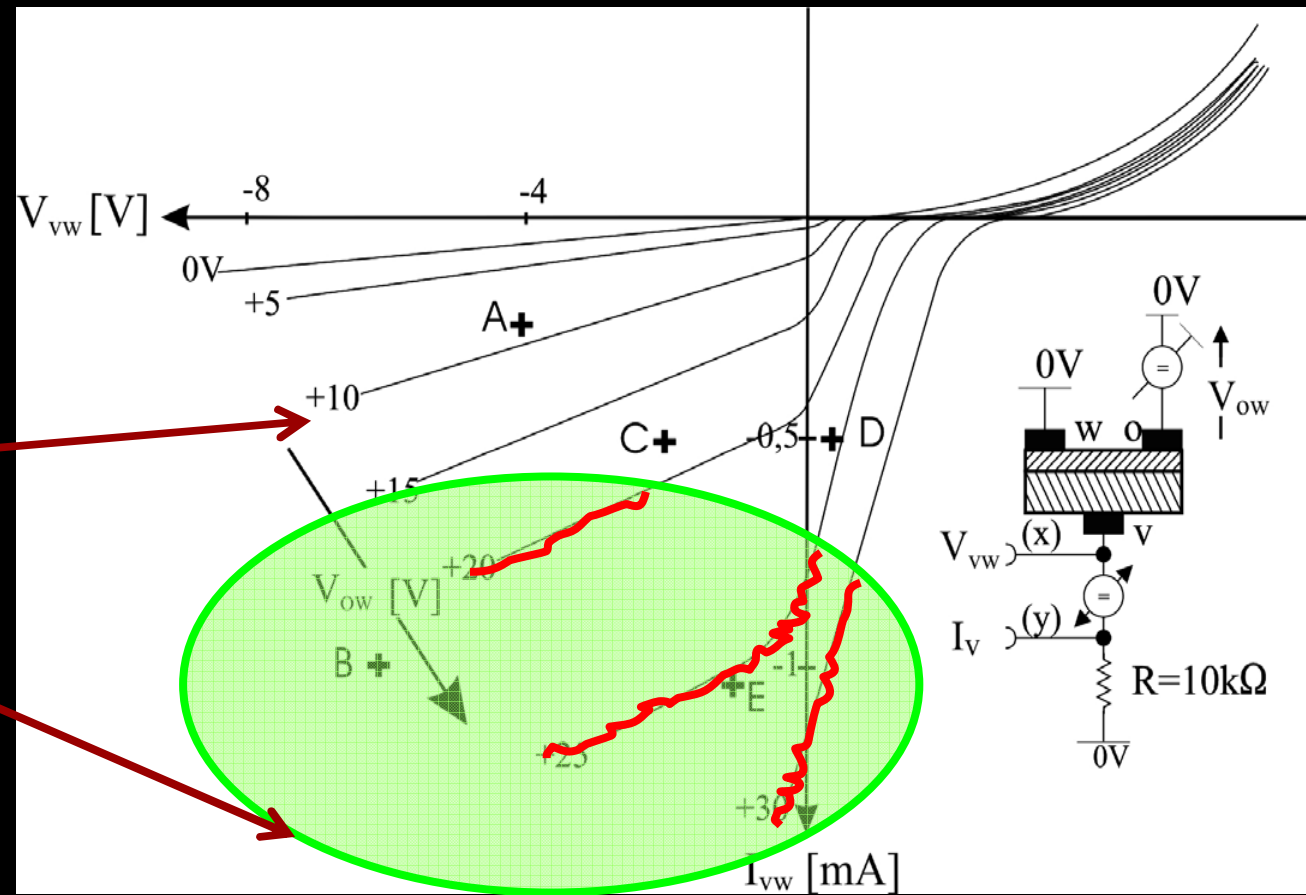
NDR of TEMPOS due to collective track interactions

example: electronic noise at high currents

no noise

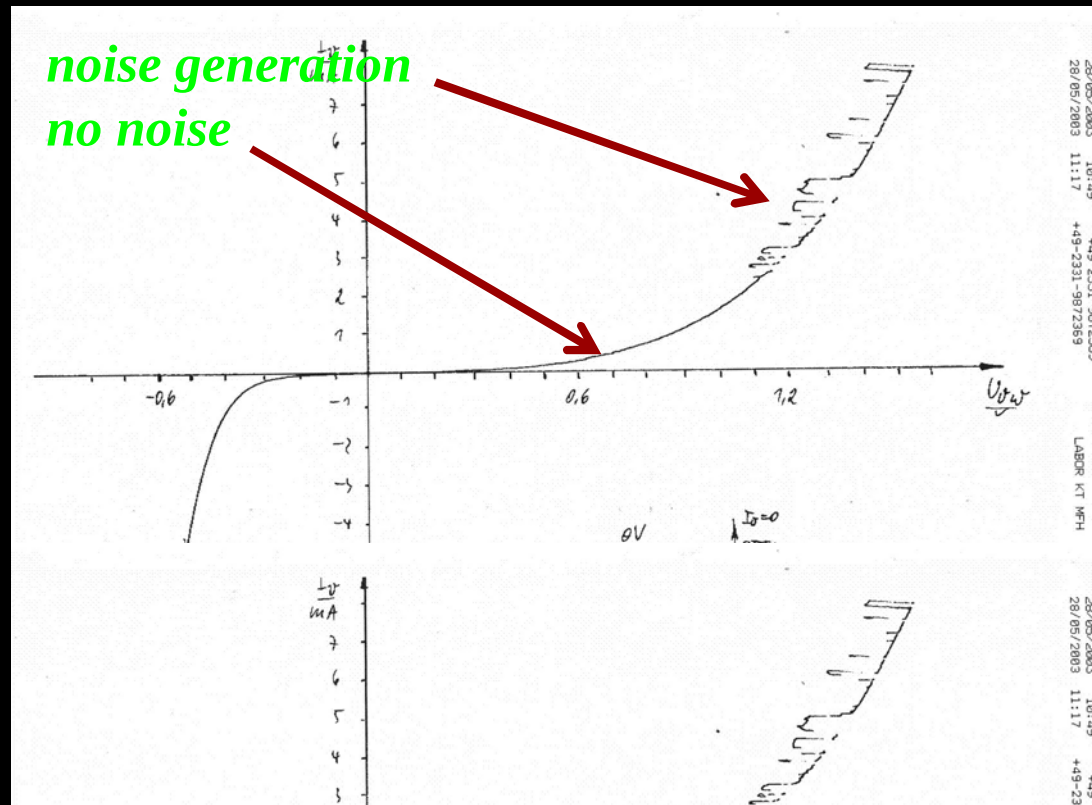
noise generation

P-type Si/SiO₂



Negative resistance of TEMPOS

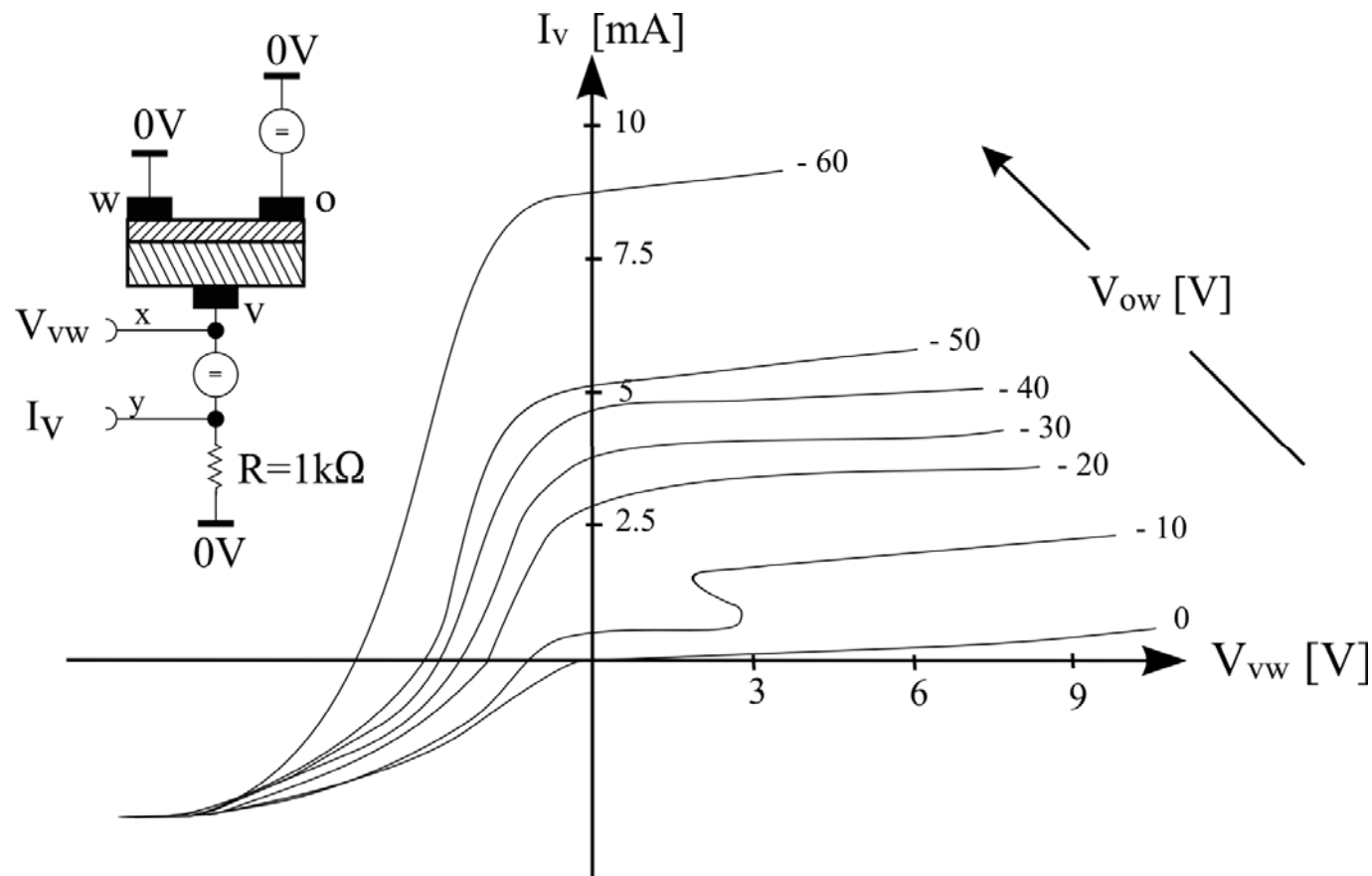
example: electronic noise at high currents



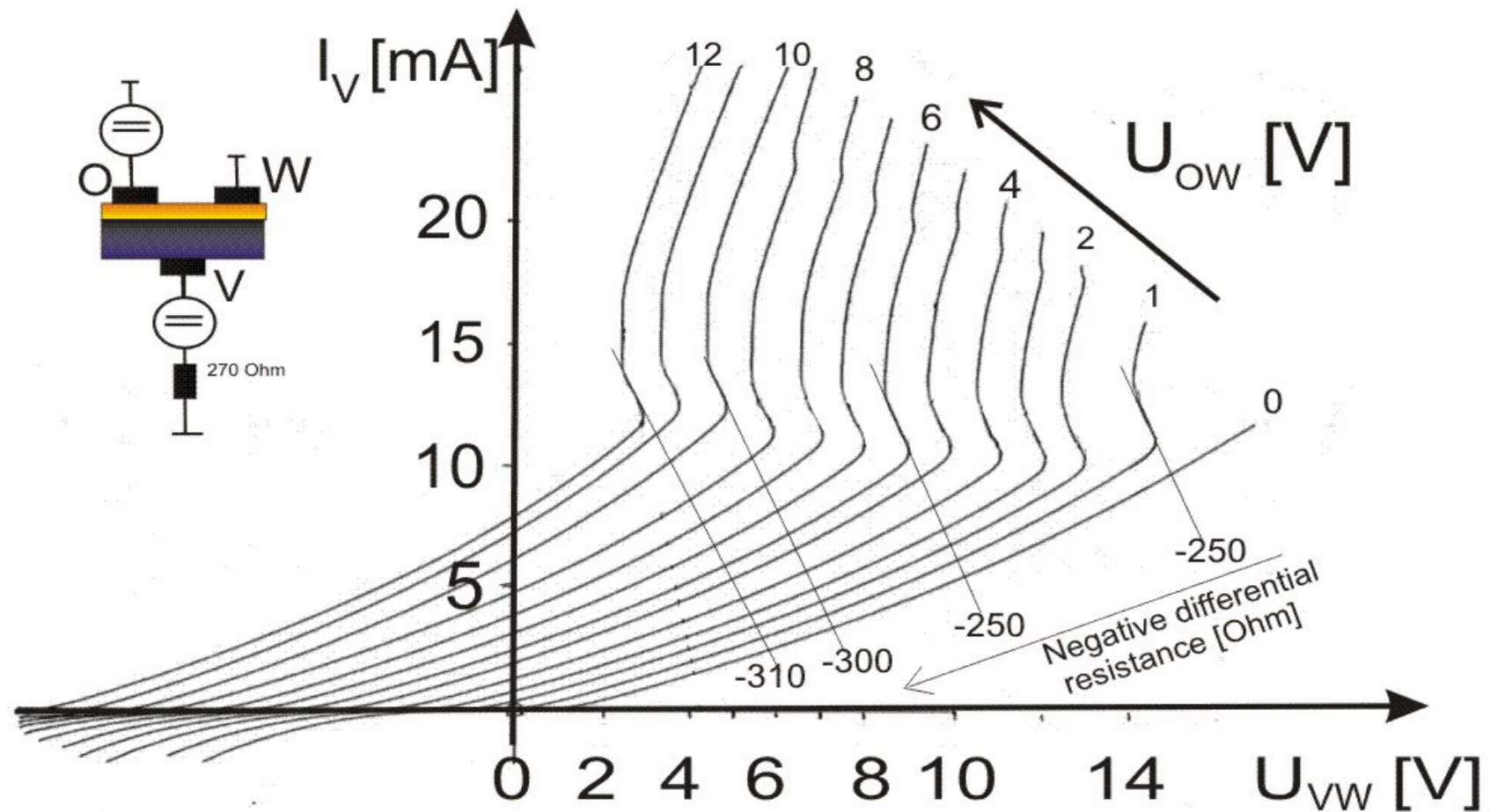
N-type Si/SiO₂

Negative resistance of TEMPOS

example: local differential negative resistance

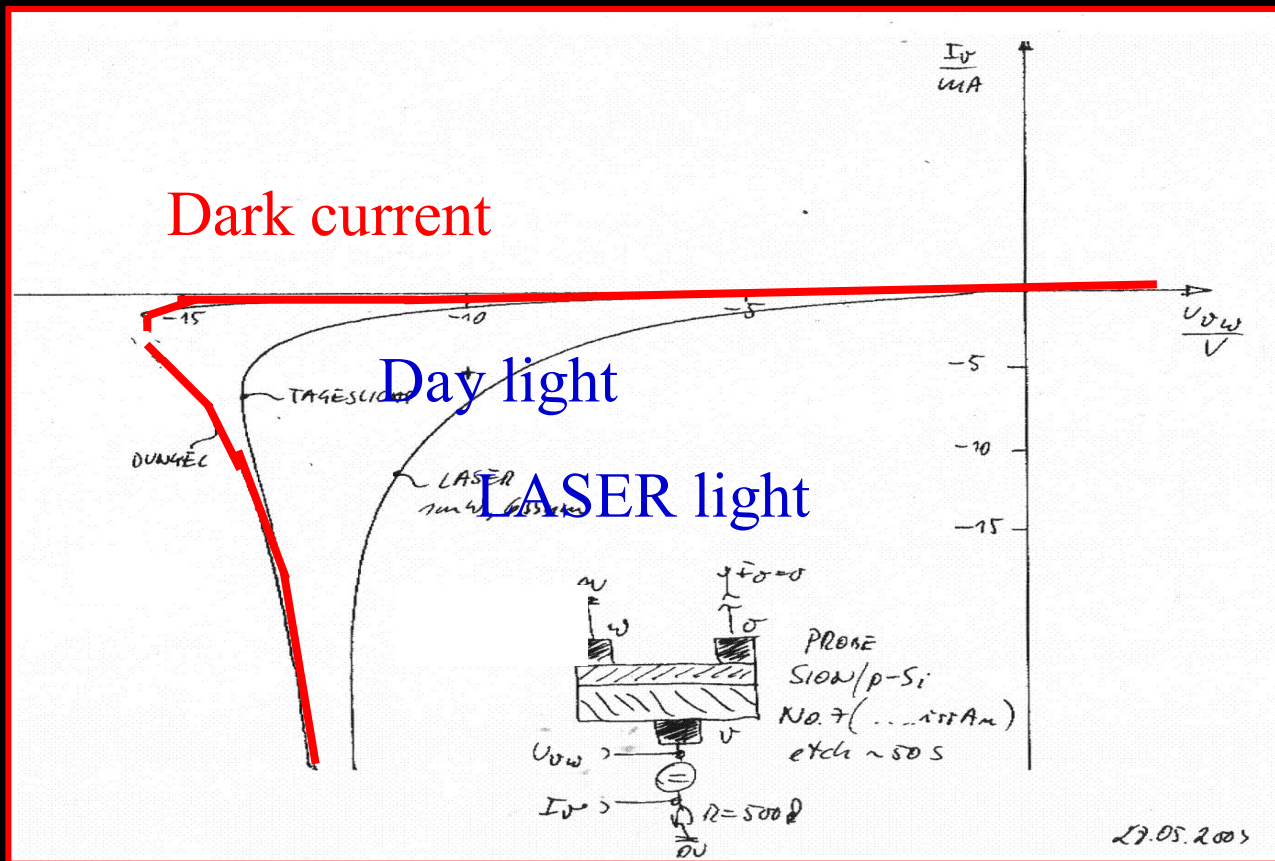


Tunable Negative Differential Resistance of Ag-Nanocluster-TEMPOS



Negative resistance of TEMPOS

example: extended negative resistance



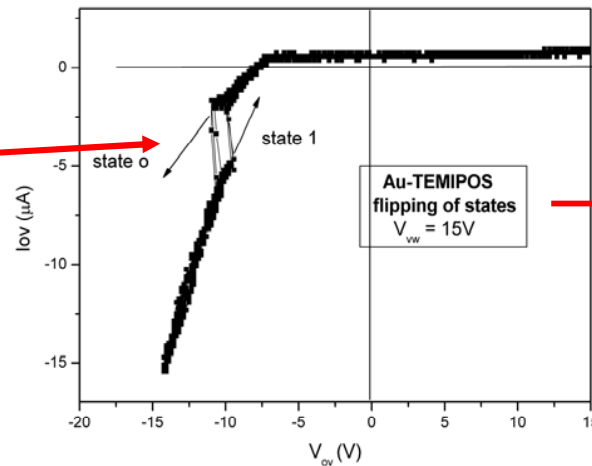
The amount of amplification can be controlled by the intensity of impinging light.

Above threshold light intensity: amplification breaks down.

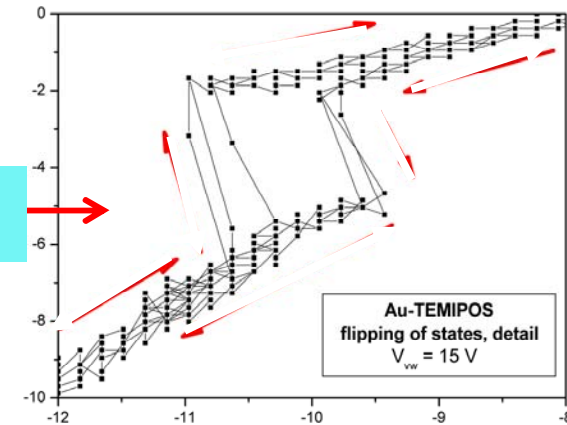
TEMPOS acts like Esaki or tunnel diode

Peculiarity of TEAMS structures: two working states + negative differential resistance (due to track-track interaction)

*Au NCs in
pores in
photoresist:*

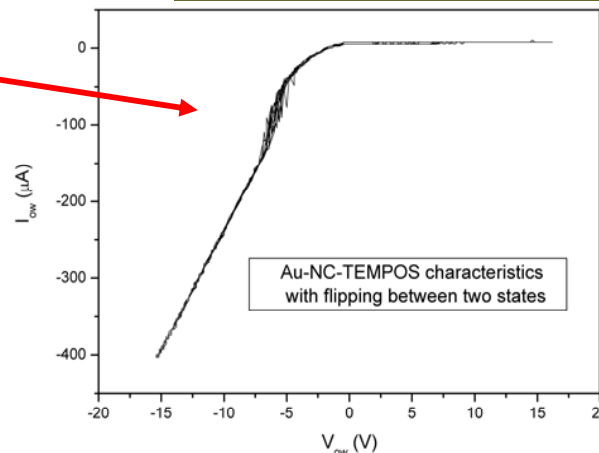


Detail:

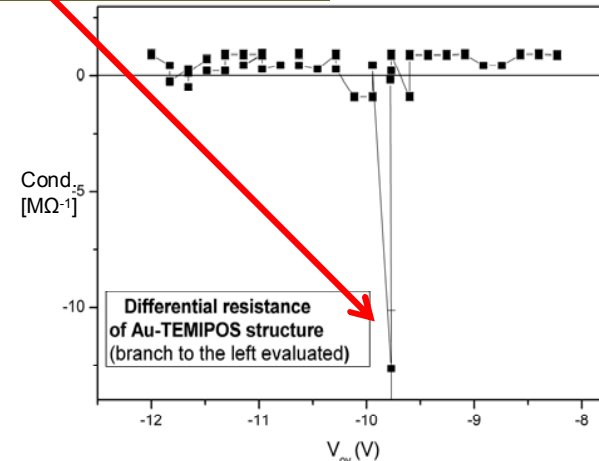


differentiation

*Au NCs
in pores
in SiO_2 :*



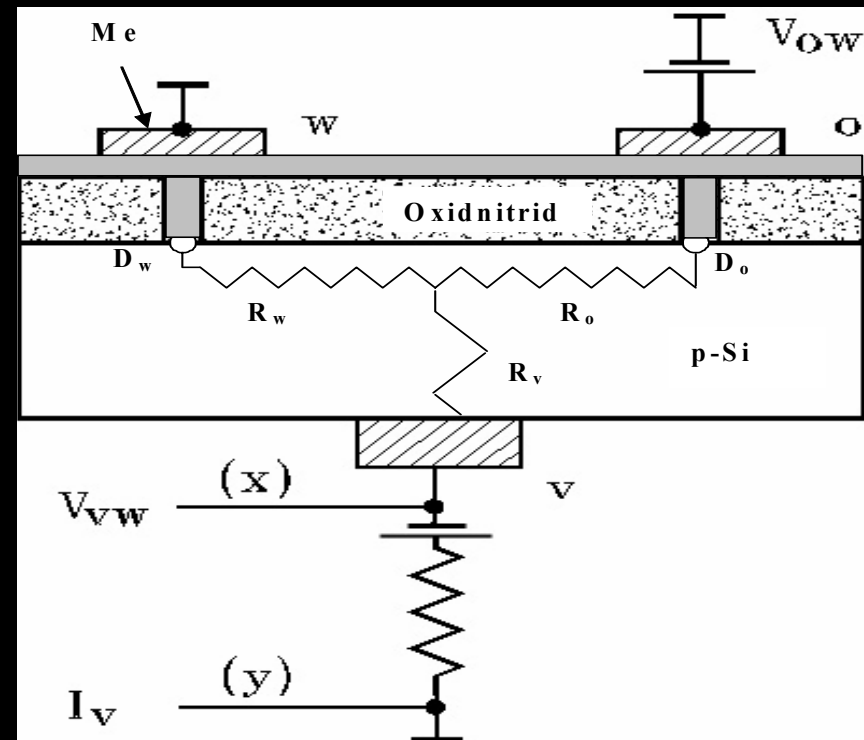
Clear localized negative resistance



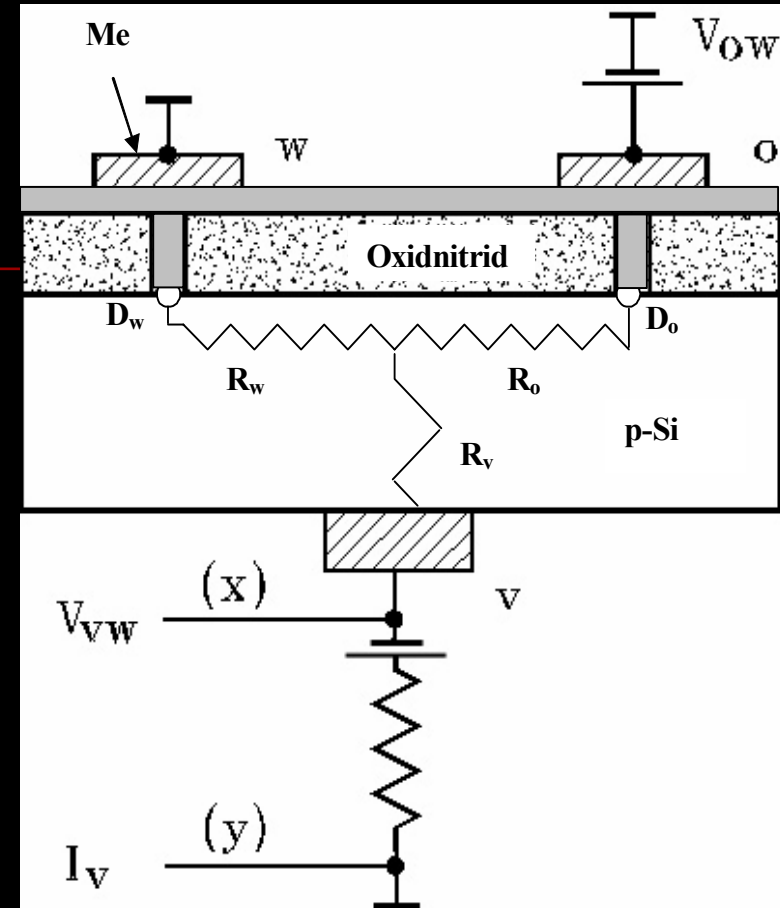
Switching behaviour of TEMPOS structures

simplifications:

- 1) take SiON as dielectric layer
→ cylindrical tracks
- 2) restriction to only one track each below the surface contacts.
- 3) restriction to p-Si only (simplest case: no inversion layers)
--> equivalent circuit



- negative voltage at o + positive voltage at v
 - diode D_o open
 - Ohmic current from v-o.
- low positive voltages at v --> negative voltage below track w
 - diode D_w backwards polarized.
- with voltage at v increasing
- voltage drop below w becomes positive
 - diode D_w becomes conducting
 - hole injection into the neighbored p-region.
 - Reduction of resistance R_w
 - Positive voltage above w increases
 - More holes injected via the diode D_w , etc.
 - Resistances R_w , R_o vanish; current limitation only by diode
 - i.e. switching from high Ohmic state to low Ohmic state.
 - Backward current/voltage characteristic;
 - negative differential resistance

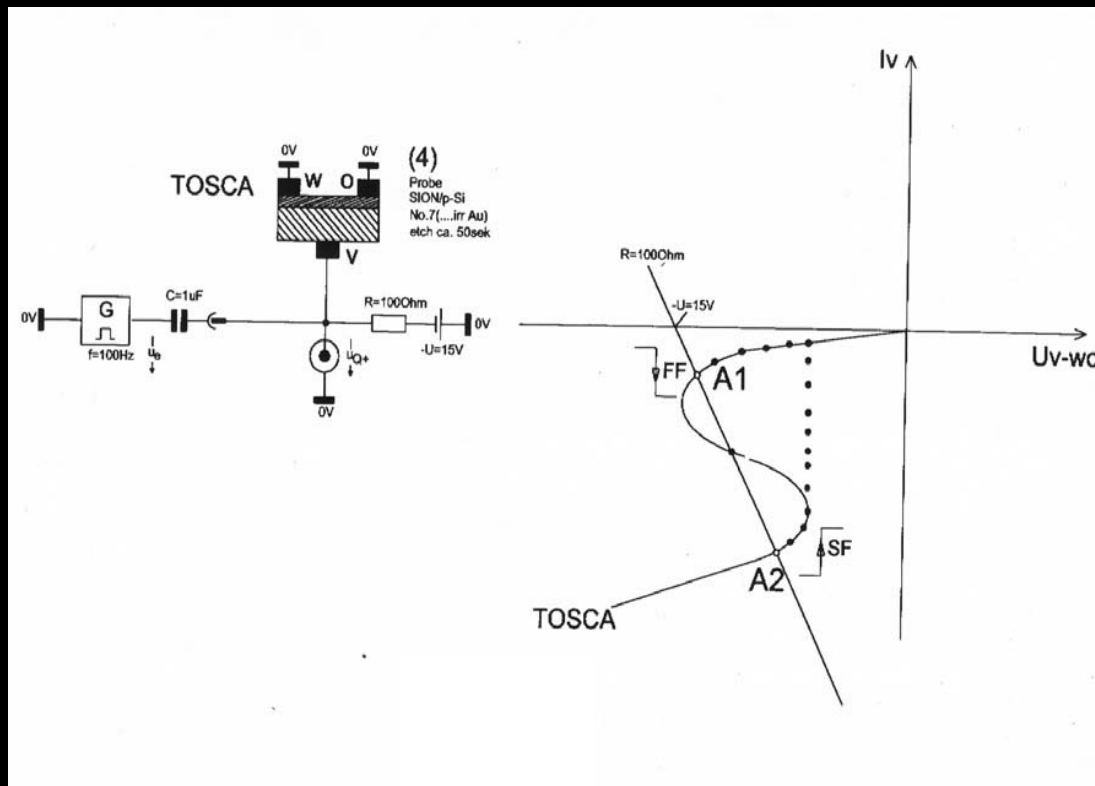


...in other words, TEMPOS structures behave similarly as Esaki diodes or double-base diodes = unijunction transistors = filamentary transistors

NDRs, Conclusions → Applications:

- **Many SITE structures (e.g. TEAMS + TEMPOS) show instabilities (due to individual or collective jumps between two working states)
→ flip-flop construction → digital electronics...**
- **Instabilities have often negative differential resistances**
- **Can be explained by collective interaction of neighboring diodes
→ application for amplifiers, oscillators**

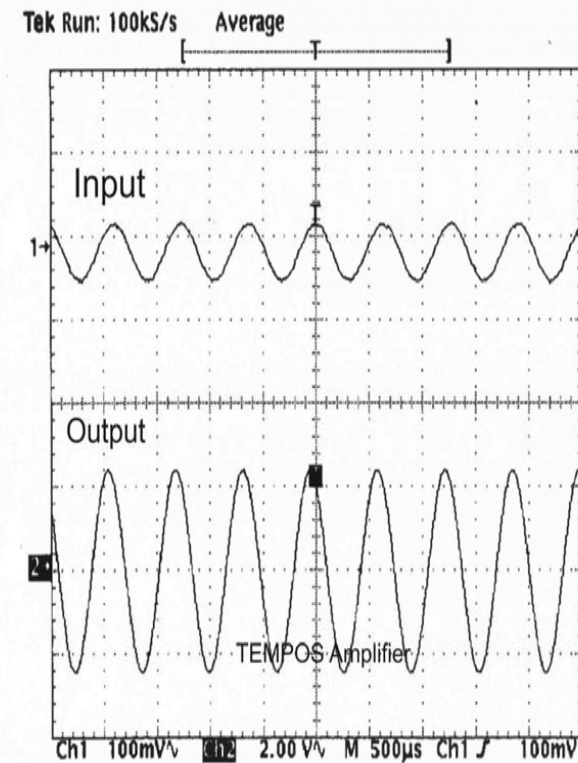
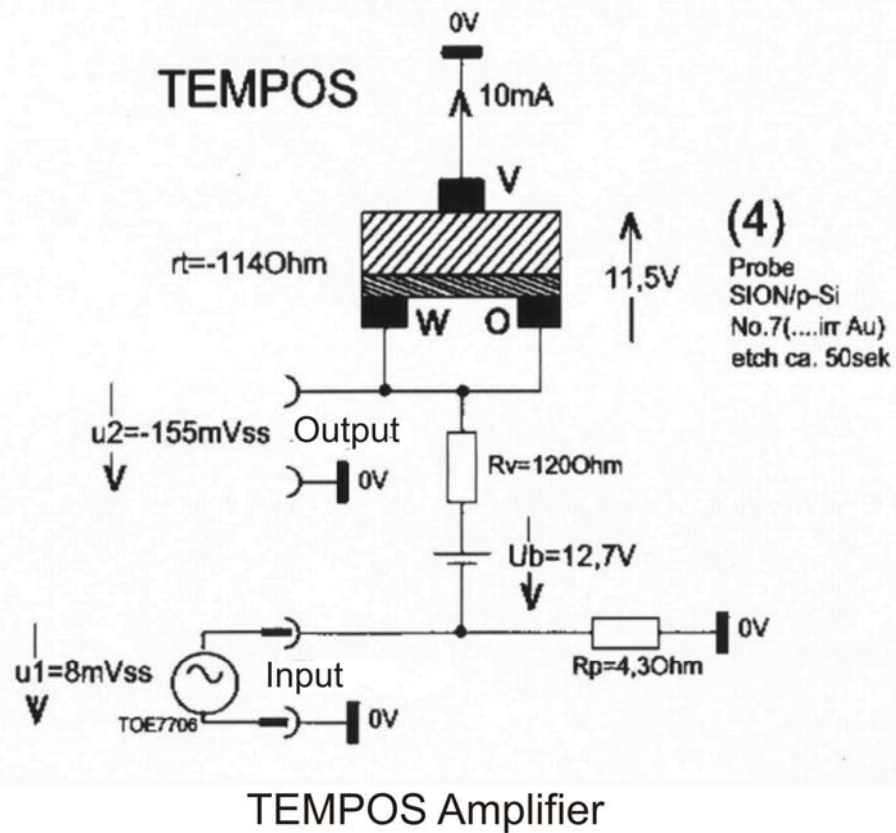
Flip-Flops with TEMPOS

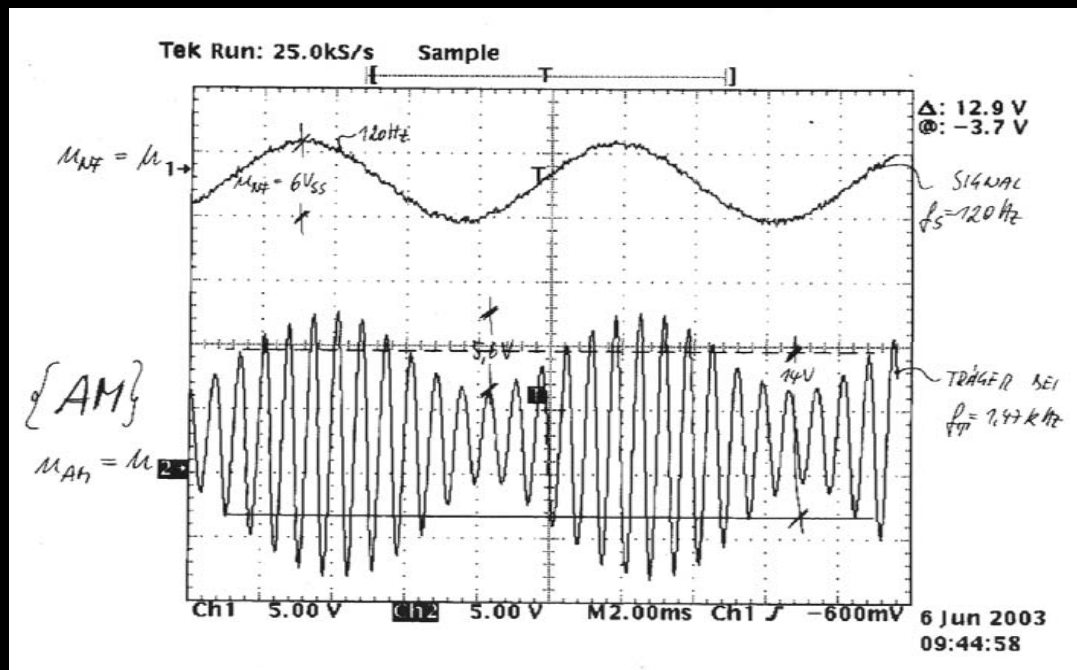
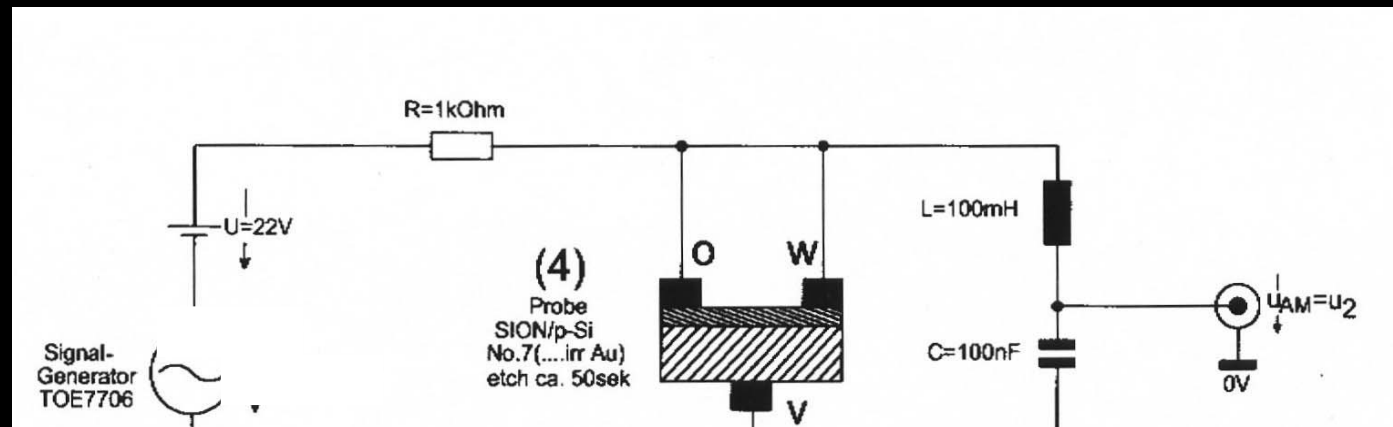


One can exploit the Esaki diode-like negative characteristics to produce flip-flops, with A_1 and A_2 being the working points.

This means, one can produce transistor-less computers!

TEMPOS Amplifier





Oscillator and AM
mixer

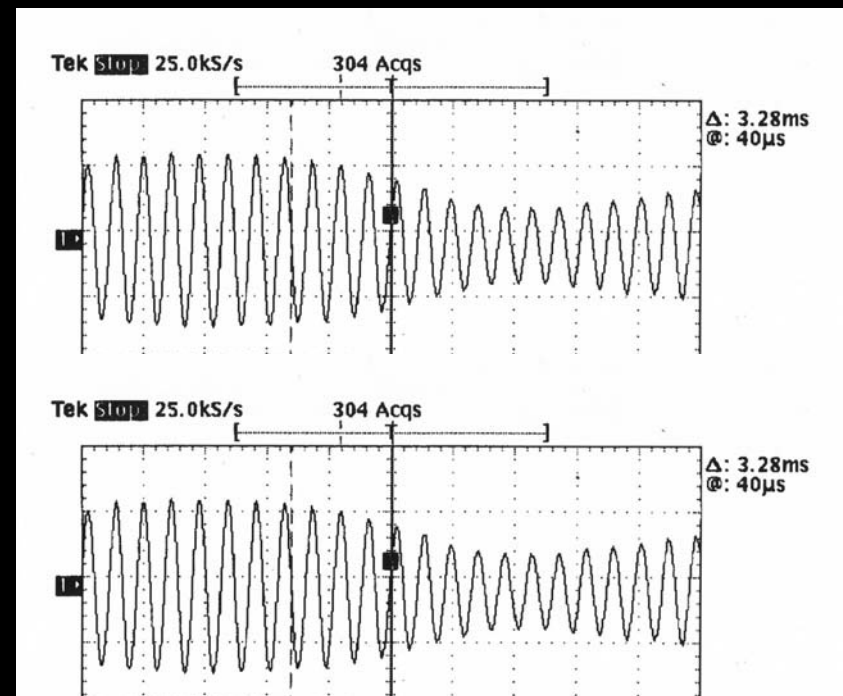
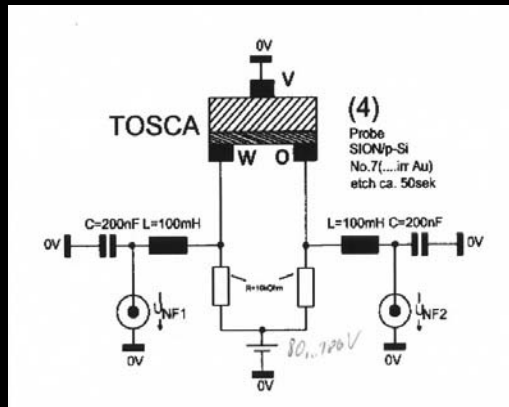
(self oscillating
AM modulator)

based on
TEMPOS

Tandem Oscillators with TEMPOS

As only one surface contact is used for amplification or oscillation, one can build tandem devices.

Attention: capacitive coupling might influence the circuits.

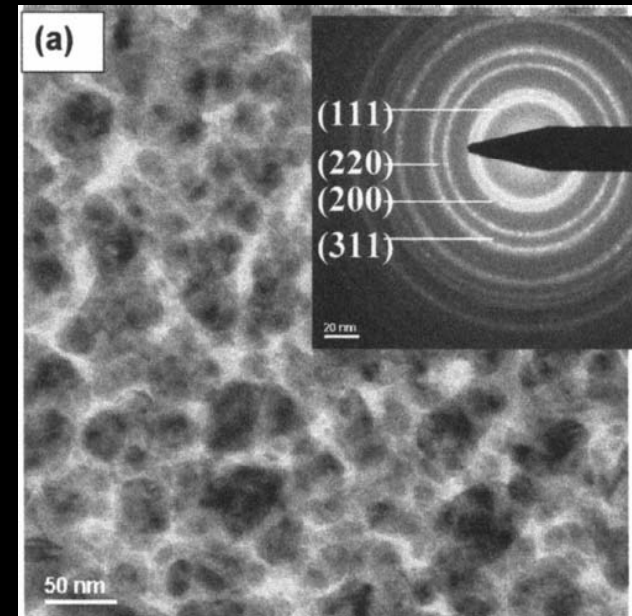


Conclusions and Outlook for TEAMS&TEMPOS:

- TEAMS/TEMPOS: in principle now well-established and understood

Future:

- Study TEAMS/TEMPOS with –
 - + metal-polymer nanocomposites
 - + biological systems
 - + diamond / EG /CNTs
- CNT-TEMPOS for 3D structuring
- direction-dependent TEMPOS sensors
- 2D position sensitive TEMPOS sensors
- intelligent TEAMS/TEMPOS systems
- GHz TEMPOS modulators & transducers

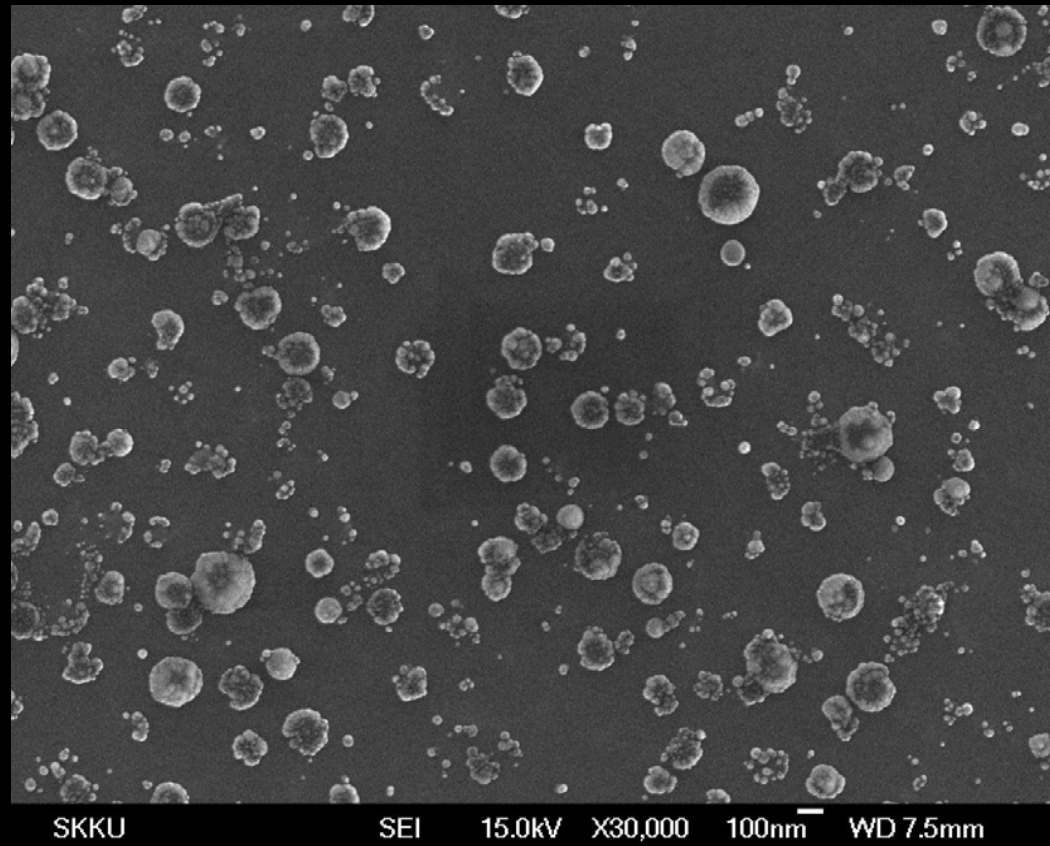


Growth of carbon nanotubes in etched tracks.

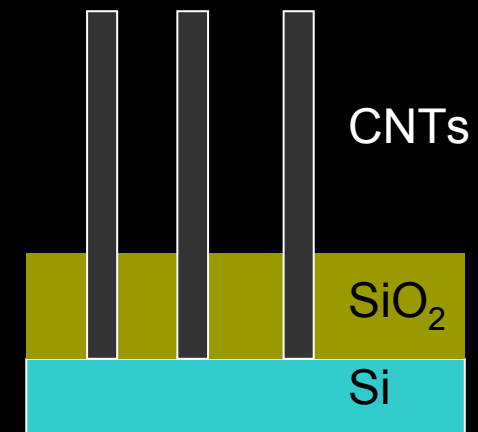
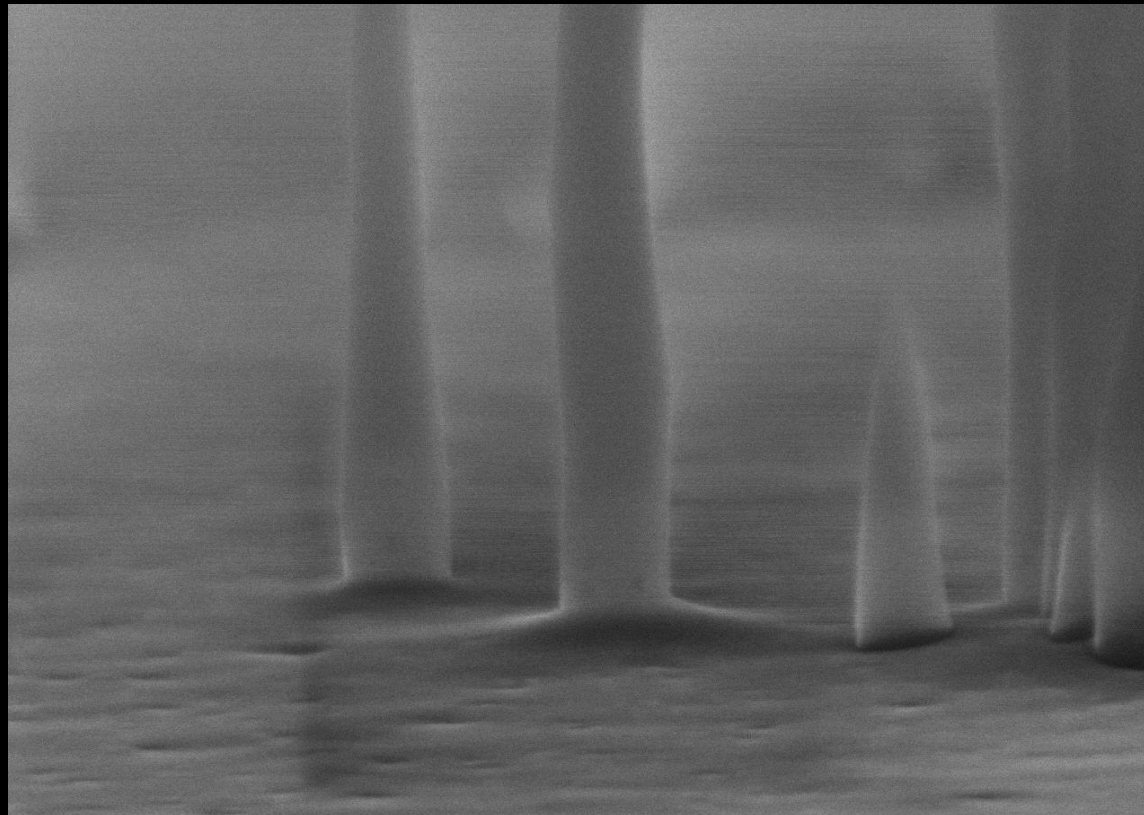
1st step:

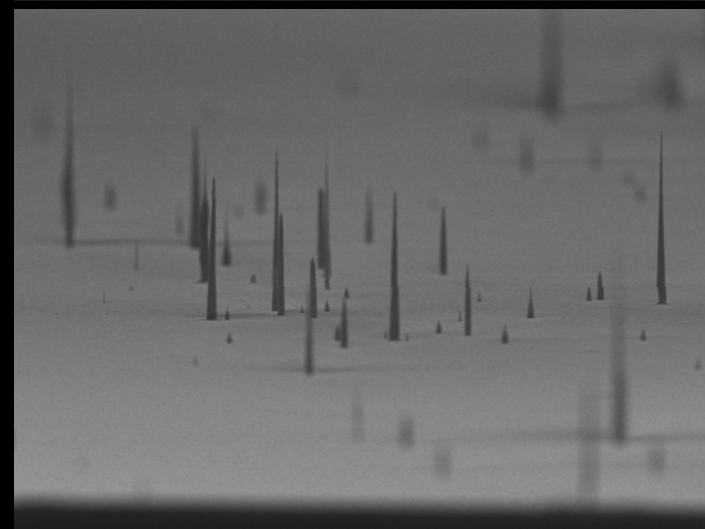
deposit Ni or Fe nanocluster
catalysts in tracks by
electrochemical routes
(~ 4 sec, 4V)

→ Growth of carbon nanotubes
with base diameter equal to
the inner diameter of the
etched tracks

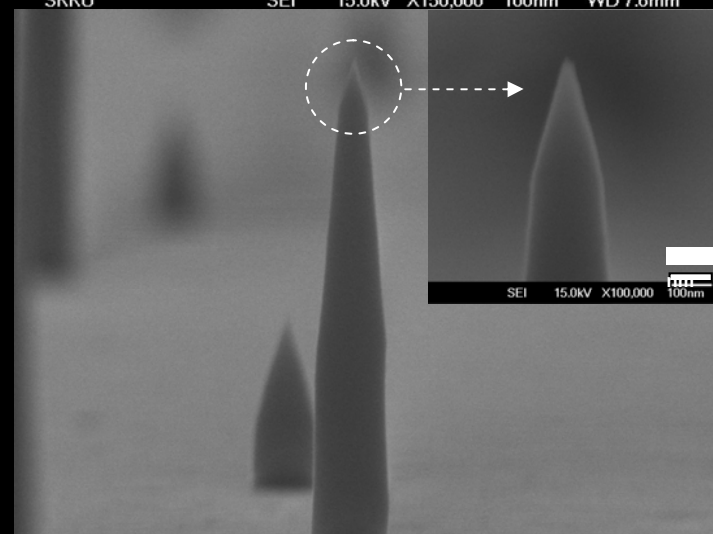
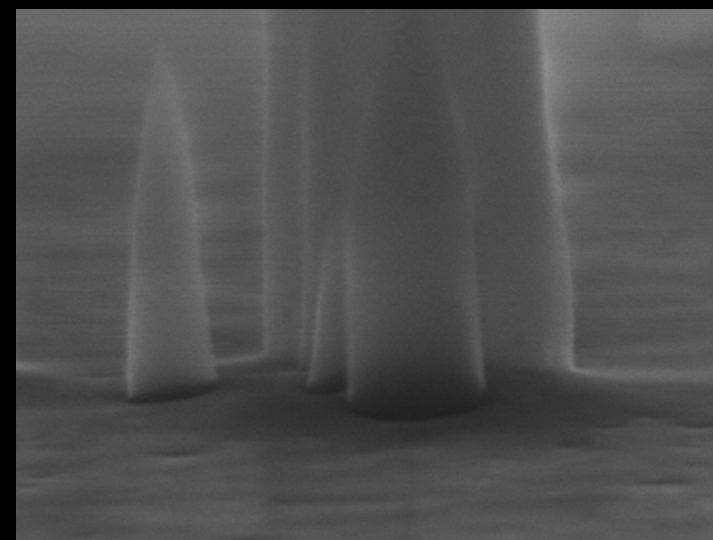


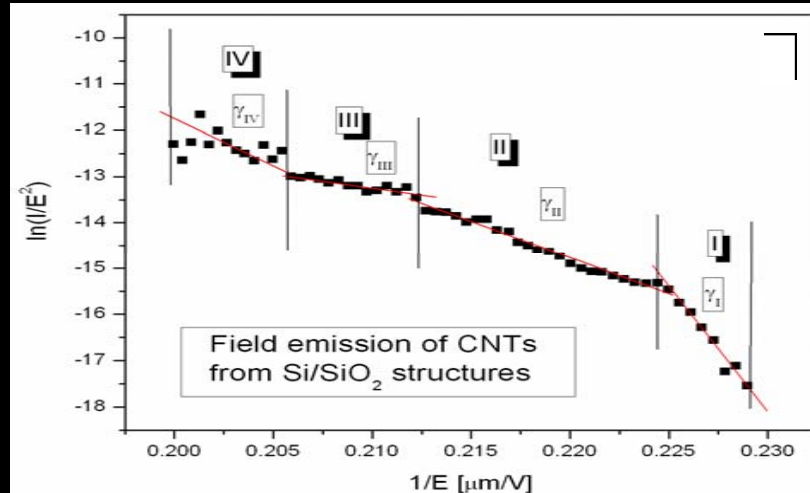
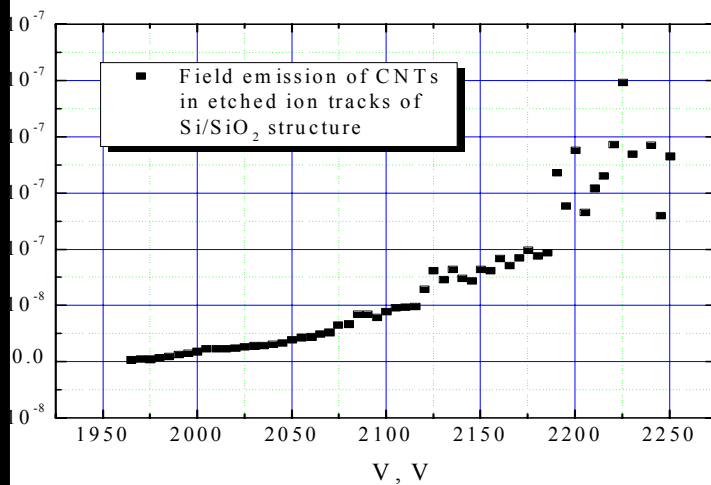
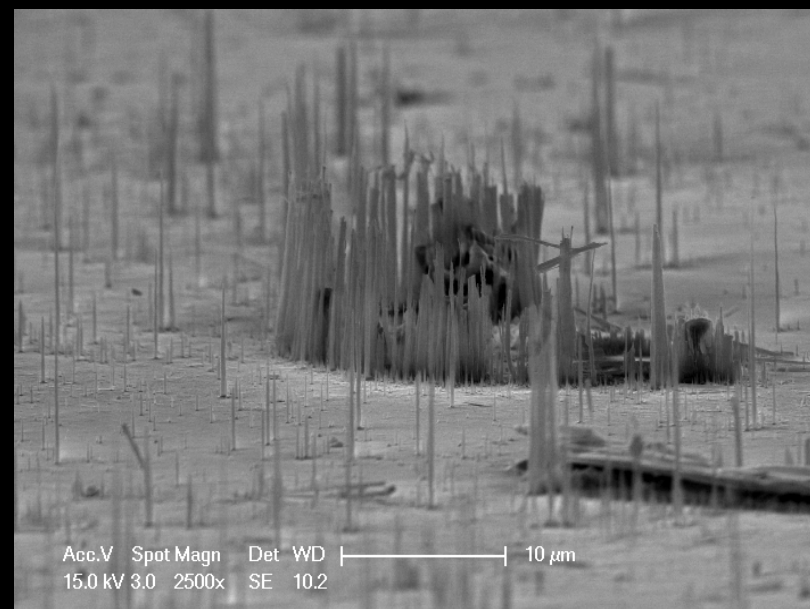
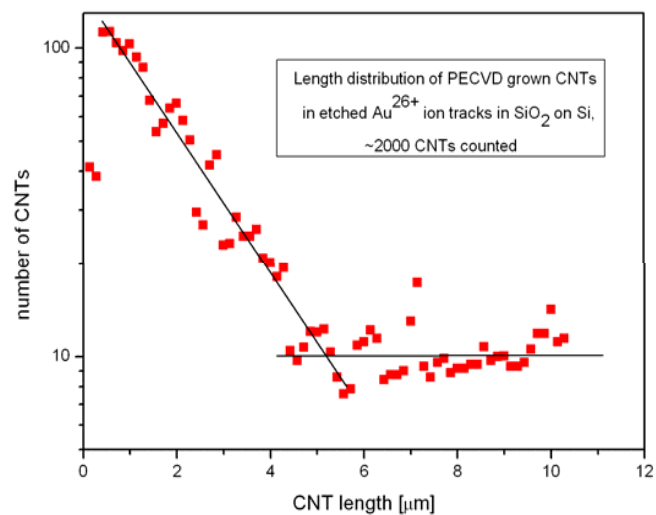
PCVD Growth of CNTs in etched tracks



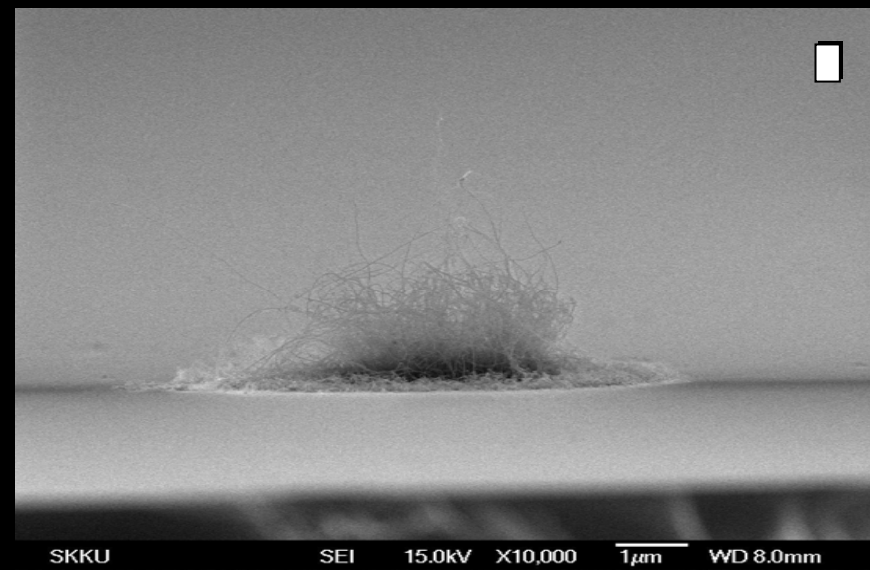
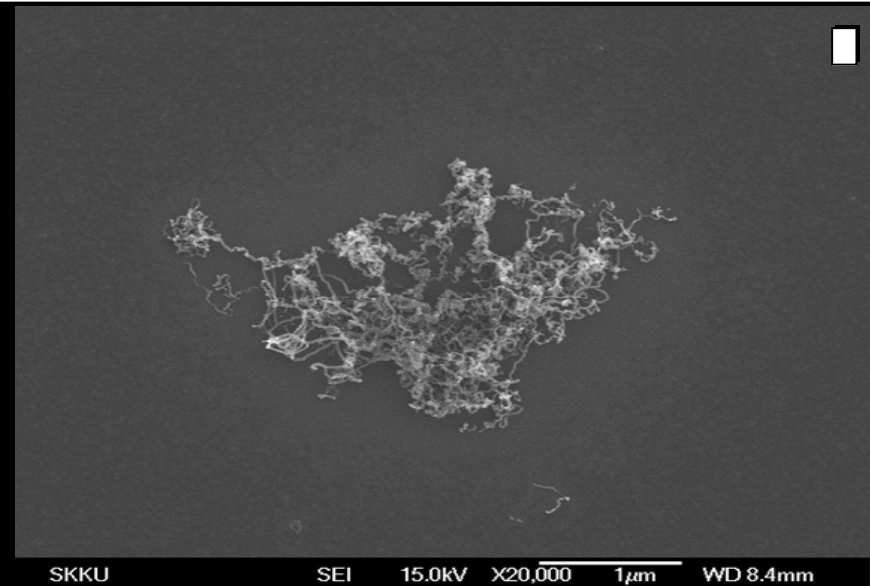


More
images
of
PCVD
grown
CNTs
in
etched
tracks



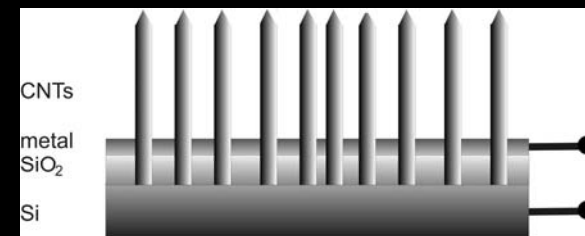
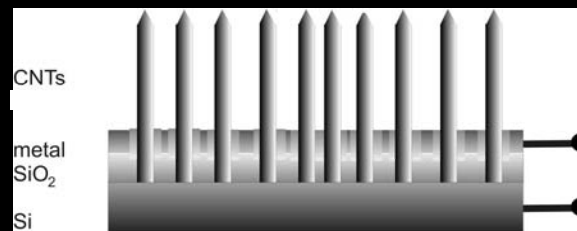
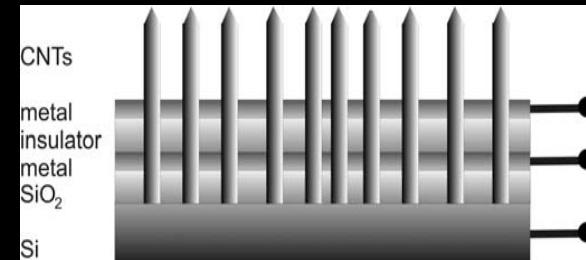
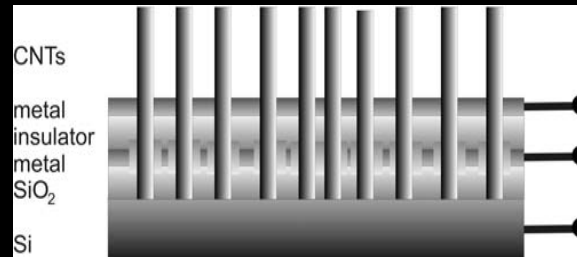


For comparison:
Thermal CVD grown
CNTs in tracks



The aim: 3D nanoelectronics with PCVD-grown CNTs

examples:



Conclusion and Outlook:

- Nanoclusters and nanotubes are valuable building blocks for nanoelectronics, specifically to SITE
- As well „classical“ as novel electronic devices can be constructed with the help of NCs and NTs
- Especially promising are –
 - * NCs for sensors
 - * NCs for TEMPOS structures
 - * CNTs for 3D nanoelectronics

Acknowledgement

Beer Sheva:	A.Kiv
Berlin:	J.Chen, J.Bundesmann + ISL accelerator team
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Hagen:	W.R.Fahrner, K.Hoppe
Kiel:	F.Faupel, A.Zaporetchenko, A.Kira, A.Biswas
Minsk:	A. Petrov, A.Fedotov, S.Demyanov
New Delhi:	A.Chandra, D.K.Awasthi
Novosibirsk:	A.Berdinsky, A.Fedorov
Porto Alegre:	R.M.Papaleo, M.Behar
Pune:	P.S.Alegaonkar
Rabat:	A.Zrineh
Sao Paulo:	M.Tabacnics
Suwon:	Y.B.Yoo, J.H.Han